

CHEMICAL HERITAGE FOUNDATION

GORDON E. MOORE AND JAY T. LAST

Transcript of an Interview
Conducted by

David C. Brock and Christophe Lécuyer

at

Woodside, California

on

20 January 2006
(With Subsequent Corrections and Additions)

ACKNOWLEDGMENT

This oral history is part of a series supported by grants from the Gordon and Betty Moore Foundation. This series is an important resource for the history of semiconductor electronics, documenting the life and career of Gordon E. Moore, including his experiences and those of others in Shockley Semiconductor, Fairchild Semiconductor, Intel, as well as contexts beyond the semiconductor industry.

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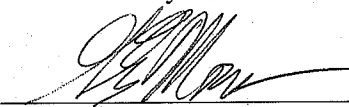
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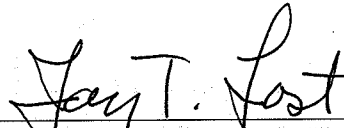
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(Signature)


Gordon E. Moore


Jay T. Last

(Date)

9/14/07

2/4/07

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GORDON E. MOORE

1929 Born in San Francisco, California, on 3 January

Education

1950 B.S., chemistry, University of California, Berkeley
1954 Ph.D., physical chemistry and physics, California Institute of Technology

Professional Experience

1953-1956 Johns Hopkins Applied Physics Laboratory
Research Chemist, Physical Chemistry

1956-1957 Shockley Semiconductor Laboratory
Member, Technical Staff

1957 Fairchild Semiconductor
Founder

1957-1959 Director of Engineering

1959-1968 Director of Research and Development

1968-1975 Intel Corporation
Co-founder and Executive Vice-President

1975-1979 President and Chief Executive Officer

1979-1987 Chairman and Chief Executive Officer

1987-1997 Chairman

1997-present Chairman Emeritus

Selected Honors

1975 Distinguished Alumni Award, California Institute of Technology

1978 Harry Goode Award, American Federation of Information Processing Society

1979 Frederik Philips Award, Institute of Electrical and Electronics Engineers

1980 Computer Society Pioneer Award, Institute of Electrical and Electronics Engineers

1988 Founders Award, National Academy of Engineering

1990 National Medal of Technology

1993	Medal of Achievement, American Electronics Association
1993	John Fritz Medal, American Association of Engineering Societies
1996	Excellence in Achievement, California Alumni Association
1996	Elected to Horatio Alger Association of Distinguished Americans
1997	Founders Medal, Institute of Electrical and Electronics Engineers
1997	Alumnus of the Year, California Alumni Association
1998	Fellow Award, Computer History Museum
2000	D.L. (honorary), Princeton University
2000	D.Sc. (honorary), University of Illinois at Urbana-Champaign
2000	Lester Center Lifetime Achievement in Entrepreneurship and Innovation Award
2000	PricewaterhouseCoopers Leadership Award for Lifetime Achievement, The Smithsonian Institution
2001	Othmer Gold Medal, Chemical Heritage Foundation
2001	Vollum Leadership Award, Oregon Graduate Institute School of Science and Engineering
2001	World Technology Awards: IT-Hardware
2001	Millikan Medal, California Institute of Technology
2002	Presidential Medal of Freedom
2002	Order of the Golden Ark, The Netherlands
2002	25 th Anniversary Lifetime Achievement Award, Semiconductor Industry Association
2002	Bower Award for Business Leadership, Franklin Institute
2003	Elected Foreign Member of the Royal Society of Engineering (UK)
2003	L.H.D. (honorary), Johns Hopkins University
2004	Perkin Medal, Society of Chemical Industry
2005	Lifetime Achievement Award, Marconi Foundation at Columbia University

JAY T. LAST

1929 Born in Butler, Pennsylvania on 18 October

Education

1951 B.S., optics, University of Rochester
1956 Ph.D., physics, Massachusetts Institute of Technology

Professional Experience

1956-1957 Shockley Semiconductor Laboratory, Mountain View, California
Senior Technical Staff

1957-1959 Fairchild Semiconductor, Palo Alto, California
Senior Technical Staff; Co-Founder
1959-1961 Head of Integrated Circuit Development

1961-1966 Amelco Corporation, Gardena, California
Director, Research and Development; Co-Founder

1966-1974 Teledyne Technologies, Inc., Gardena, California
Vice President, Research and Development

1980-present Archeological Conservancy, Albuquerque, New Mexico
President

1980-present Sierra Monitor Corporation, Milpitas, California
Director

1982-present Hillcrest Press, Inc., Santa Ana, California
President

1998-present Think Outside, Inc., San Jose, California
Member, Board of Directors

Honors

1999 Hutchinson Medal, University of Rochester

ABSTRACT

This oral history with **Gordon T. Moore** and **Jay T. Last** focuses on the years 1956 and 1957, during which time Moore and Last worked at Shockley Semiconductor Laboratory and Fairchild Semiconductor was founded. This transcript is about the life of ideas and the people who brought those ideas to fruition; Moore and Last reflect on their experiences during these years while flipping through an old notebook that documented various aspects of the meetings they had over an eighteen month period. In order to fully understand this oral history, the reader must consult the Supplement to Gordon E. Moore and Jay T. Last Oral History, oral history number 0327S, which is also part of the Chemical Heritage Foundation's collection

INTERVIEWERS

David C. Brock is a senior research fellow with the Center for Contemporary History and Policy of the Chemical Heritage Foundation. As an historian of science and technology, he specializes in oral history, the history of instrumentation, and the history of semiconductor science, technology, and industry. Brock has studied the philosophy, sociology, and history of science at Brown University, the University of Edinburgh, and Princeton University (respectively and chronologically). His most recent publication is *Understanding Moore's Law: Four Decades of Innovation* (Philadelphia: Chemical Heritage Press), 2006, which he edited and to which he contributed.

Christophe Lécuyer is research historian at the Chemical Heritage Foundation. He holds a Ph.D. in history from Stanford University. He has published extensively on manufacturing districts, university-industry relations, and the history of electronics and scientific instrumentation. He was a fellow of the Dibner Institute for the History of Science and Technology and taught at MIT, Stanford University, and the University of Virginia.

mpu } Chem projects
 mp

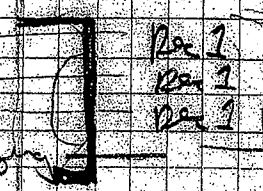
low coffee - careful - discuss control

States

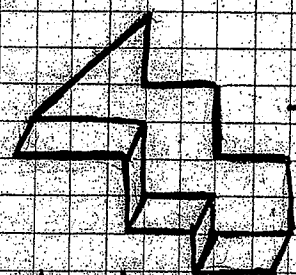
10/5/57

The lab - 3 weeks from today

- power
- rooms
- cabling
- next passing



Rec 1
 Rec 1
 Rec 1



- phones -
- positions -
- Wed Tues - Thursday
- cabinets out for bids

Plumbing contract not out

Domica

- Power in small rooms -
- Lay out office

Run H₂O, O₂, N₂, A ?? (pl no further S?)

- Distilled H₂O

- personal requirements -

11/6/57

10 - NPN computer - GEM

Power oscillator - slow depend on photo resist RUN

12 - PNP " - JAH

→ PNIP }
 NPIN }

Materials -

* DCTL - Direct coupled - low substrate impedance (NPN) - D.A.3
 Transition layer

* Power switch - 2.5 hp power - 50 amp a.c.

Staff meeting 11/11/57. Max + Max.

hourly vs monthly stream way

Requisitions - Project leader to \$1000
" " + Bob 5000
75000 Policy committee

Cardex files?

Tool list

Receiving order standard date.
procedures will be written up by Max
write up

- Patent Attorney -

Staff Meeting 11/18/57

- power transformers low: 2 weeks to go Finished by 12/2/57
- ceiling: started today 2 weeks 12/2/57
- (this is only ~~power~~ main power - no bench power)
- plumbing, sewers etc } bid out
gas, air
- air handling - blowers, pressure: bid out.
- small rooms: 12/15/57.
- benches & cabinets: Finished by Dec 1
cabinets: arrive this Thursday - also 6 Hoods
- benches: arrive today
- phones: no estimate 2-3 weeks DA6-6695 in 2 weeks
4 benches

two estimates to J.B today

- 1 up to 12/31/57
- 2 up to 3/1/57

Hodgson called:

officer 126
Devito mgr.

Condy file: CSR

Patent agreement, rather to steel (mining).

Patent attorney: Flax & Saxon - wait on this.

When do we want to get into production.

Jan 6	Securing Orientation Scaffolding (reactor) Crystal evaluation	JB CSR JTC	⇒ transfer to production date shown
-------	--	------------------	--

Mar 3	photo etching training diff NPN	R.N.N. JEM
-------	------------------------------------	---------------

Mar 17	exp & alloy	JEM
--------	-------------	-----

April 1	assembly NPN	R.B.
---------	--------------	------

April 15	test & selection	JAH
----------	------------------	-----

May 5	PNP diffusion	JAH.
-------	---------------	------

June 2	polish to thickness	JTC
--------	---------------------	-----

June 15	PNIP	JTC
---------	------	-----

reprocessors for production - low tech shells in general
we will produce specs

Dec 1	Jan 6	Feb	13 more tech people by 2/1
1 Fed 1 Tech 1 Mech 1 Prod	2 Fed 2 Tech	2 Tech 2 Fed 2 Mech	2 more 2 more
6		3	

Engel - write him saying no real interest

25

Mello - low impervious JAH. 3 hrs at PSI. - invite hi up.

hire people thru agencies at the moment.

Staff meeting - 11/24/57

Buy coming 1050 lbs \$2600 Jan 1

in and out baskets -

new P.O. procedure - J. B. signs all P.O.'s

Birdie transistor requirements #106

Power - transformers arrived today
power turned on Dec 7.

Plumbing - ?

Ceiling - first half - first of next week.

Painting - start today - 6 days work

Cabinets - here
Furnace burners -
hoods - here

Tops -

Phones

Distilled H₂O - in the lounge.

RF Generator - on its way

Hodgson: security clearance - see Russell

patent attorney - Contingent fee

Minsky's bill Hodgson quotes \$10,000 total bill 25K

Hodgson's bill Hodgson quotes \$10,000 total bill 25K

Steps of ~~patent~~ agreement with Bell

- 1) patents only
- 2) technical design + patents
- 3) " " " + 25K adv. royalties

Staff meeting 12/3/57

titles S.C. Technician
electron technician
Project engineer
Sr project engineer

DDK: KEP Inc. LKB
\$250,000 Ford

Manager Friday N.Y. Times ad.
Wall St. Journal.

John WEOMA
Elect. Ind. Assoc. → personnel price
↓
→ register transistor types
(to have a # that will
stick with first
announced)

Patents: Hudson will sign a patent agreement.
Bey: - sign stock agreement.

more transistor - do we want to make this
transistor
U.S. Patent
Material

For:
- product money
- available market. (a contract)
- point out prod. problems -
- not need long term commitment)

Against
- now common available
- against the lic. by S.

Timing 12/2/57

Power - cut over today or tomorrow

Plumbing - about 75% of work

Light - tomorrow

Ceiling - coming along OK

Rooms - rubber mulling outside only \$280
completely finished beginning of next week

Main lab Exhausts: \$2500 incl 4 blowers

Phones -

RF Strata: this week

Tops: start to double in soon

Wax floor: sometime this week

Poly sinks - BIND -

BLOWERS:

SLICER: this week?

Personnel → to E.K.

Max after everybody is hired

Rate of Abandonment of tech personnel - ~~Not to do any more~~

to production

E.K.

Supervisors - some tech skills - in charge of

tech prod.
diffusion
service ass't

city group

local girls

employee evaluation by senior personnel -

we will need BS MS engineers

if we want to add people we will have to start soon

15 tech staff - 21 employees

we can work up to 30 people

5-6 technicians new

about 5 engineers

Pres leader
of new
technicians

\$500-600

Coffee Committee
Parker
Hess
Clifton
Klein & Co.

12/9/57

Staff meetings:

Half visit: accurate forecasts on budgets sales

Fairchild organization

Fairchild Controls } Computers
Electronics
etc

↓
wholly owned subsidiary of Fairchild Camera

applied for security clearance for facility as Fairchild subcontractor

Modest → Harlan Sawyer ← 200 →
Beauchamp → Phil Peeters ← 375 ← keeping contact books - making shop work.

Technician Paul Hinkelb 1/2/58 400 Bus Ad
Sawyer 400 Criminology

by end of March:

3 sales 17 technical
Phil
Max
Halcy

17 technical } by Jan 1
Technician
Janitor

23 new

Kalgrawig
Sales
custody
Sr Engineer → Jan
Technician - Robert Jan 20
Technician - Robert Jan 20
Sr Engineer - Finch
Technician - Jan Feb
Technician - Finch Feb
3 technician - moved for people
going to production

total 38

Change at secret for
Production Staff in this
budget.

⇒ make out a project budget: ³¹ equipment
expens. material

(get predicted schedule from Bdr)

write purchasing procedure PO costs us \$10-25
no charge accounts PA Hardware, etc.

Alla Chelsey - prospective Mgr.

Ad - Tom or Wood for a Mgr.

~~Power~~

Facilities

Power: ON.

Secondary power: Owens doing now

Plumbing - almost done - leak in gas line

Secur in some more Cu tubing to go -

Ceilings - almost done.

Partitions - being painted now.

Bechs: start in on Wednesday

Wax floor this Tue perhaps

Pipes: all done

Poly sinks: lag line still 3 weeks to go

32.

Staff Meeting: Monday Dec 16.

Chief of Air Force security Wed A.M.

Baldwin - Head of Product Engineering

Facilities:

Power: primary OK

secondary: all will be done by Owens to banks
some plugs on benches.
all in the week.

Plumbing: - waiting for sinks & bench tops

Gas handling: waiting for valves

Poly sinks - 3 weeks to go:

stainless steel will
come in with sinks

Lab bathroom sink -

Hoods:

tips: ~~to~~ many in today:

Exhaust system - recirculating systems.

Electrical 14K -
 Ceiling -
 Partitions
 Plumbing - 5
 Phone
 Cabinets
 Taps
 Tool holding
 Components
 Pads etc
 Floors -

Tool hold 40K
 Off equipment 20K
 etc

Purchase orders: want a written procedure

Welder and Tor
 cold welding press - ~~1000~~ ??? ER = NB soon -

Monthly payroll: about 25K by March ~ 30 people

Employee Relation Committee:

not a grievance committee - just to set policies
 purchase of material from company - \$5
 Cal tools overnight authority - back of tool holder
 coffee - catered \$125 gallons 10 AM.
 3 PM.

34

Meeting 12/23/57

message -

Meeting 12/30/57

- Distilled & D.I. water -
- Fume hoods -
- Blowers -
- Paints - another week

- wire up micro-mach - Hall to do some thing

two technicians needed - CSR
Dr. Smith

technicians
two coming early Jan 2

Welder - hot welder order - due Jan 30 -
no cold welder ordered yet

\$75,000 spent in Dec.

a detailed Budget is needed month by month -

inventory system needed

1/2/58 Report on IBM meeting R.N.N.
Dec 20

35

3 general categories

low power 150 mW at Room temp
 core drivers 1W
 servo drivers 1/2-1 amp 10W out at 100°C. (Available from GE, TI)
 ↓
 selection restricted for

What they want for computers

	would like	can get (hpn, related)
collector saturation Res	10 Ω	100 Ω
input resistance h _{ib}	39 Ω	50 Ω 1 mA
h _{fe}	70	80 20 mA
transistor base f _{ob}	20	30
C _{ob}	1.6 μF	20V
collector breakdown V _{cb}	40V	725. Used in a 28V system
power dissipation P	125 mW	1 mW/°C

they need good matched pnp's to go along with those.
 (can be done only be done with double diffusion - no metallization techniques visible)

Reliability - GE pre-bakes at 200°C.
 known better than glass seals.

Want to cut out all random catastrophic failures
 put in a detergent filled bomb at 50 psi -
 shock tests

Tested Co.

Samples by end of first quarter - 20,50 or 50.
 Quantity requirements in a year. 20-60,000

36 they will go to $I_b + \text{air-conditioning}$ if they can't get Si
 clamped RC coupled logic
 haven't thought in terms of large signal parameters yet.
 symmetric transistors to simplify the logic

Core Driver

DC I_c 150ma 60-100

f_{α} > 2 mc

h_{ib} 30 Ω

1W @ 100°C.

(not realistic)
 $\approx 250\text{ma}$

β

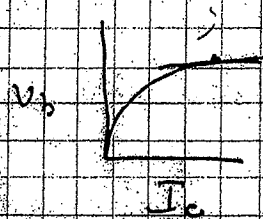
V_{ce} 60V (this is high)

R_{cs} 2 Ω

(can get 100 Ω)

V_{eb} 2V

rise time $\approx 25 \mu\text{sec.}$



should be specified

$I_c = 150\text{ ma.}$

$V_b <$

$I_b <$

designer might
 need come close
 to this.

They will use 2000-3000 of these now (contract not new).

10 computers at 100-200 each. will pay \$100 each
 for first 500

- this will be used as a high freq power switch -

main thing - get the saturation resistance down! loadside
 diffusion

this is a point area in transistors at the moment -

De
Tomson
Hughes
Metwala
Rafter

} all getting into 5mc area.

⊙ Edpro - Pioneer - using to drive servo amplifiers
low freq (DC).
gen at 100°C (also gain at -50°C - need
good lifetime for this)

Diffusion advantages:

make pnp
high α
oxide mask - interdigitate
put in intrinsic layers.
uniform large area.
low base resistance
easy to collect heat sink
(avoid encapsulation)
handle a large no. of elements at once

Disadvantages

lifetime (low β)
hard to make contacts.
(high saturation resistance)

∴ push any pnp.
interdigitate

smallest island 5x5 mils. at the moment.
completely surround the emitter.

should we head for the core drive now?

get top side structure on up

try to jack β up.

both side diffusion as soon as lapping is in good shape

Bob Noyce a mistake

~~problem~~ & cutoff no problem now -

Jan 6 - 1958 Policy meeting

Poly sinks - one - lost Friday

Mainjolds

1 hood by Friday

Evaporator working

→ check all Beauty queen cabinets →

→ clean up as soon as possible →

Interest on loan will be about \$50K a year

Budget summary

Oct 1 - Dec 31	total salaries	45 K
	op expenses	80 K
	Capital exp	91 K
		<u>216</u>

1958 - whole year - budget	
salaries	334
op expenses	360
cap expenses	216
	<u>910</u>

1959 - first quarter 27

Total 1,388,000

thru March 1959

R&D technician in Feb (UCC)

Get into March
for end April (year)

Σ = 12 = 150K for 1959

Administration

Supporting 40 K

Production 23 people EK + technicians 958

Feld	- has 3 technicians	} transfers	E = 48,500
Nov	1		
April	2		
May	2		

Do we want engineering people full time in production?
 Who does what has to be defined in detail as far as transferring things to production.
 At what stage is this necessary - as soon as it is work smoothly

we can get a leaders list

Jan 20 - members of Finance Board coming - Collins

Managers - get Baldwin up again to see Hodson next week

Bar Fisher - out for this week - on 8th or 9th
 expense - plant management - In. Procurement
 → Shil Cole now

John Byer -

Hodson - Cornell - Pauline

Wendell - talked to - Syosett 5% salary type
 down - get along well search for help?
 → out the month

90

1/13/58

Diffusion - no hood, DI water
La Co OK
Sb - just getting started - oxide masking not working yet
P - " " " "
B diffusion OK - can be oxide masked (24 hours) 10
Red P OK - up to 5×10^{20}
changing to Sb - to get thick oxide - up to 3×10^{20}
Make an n-p-n junction with Sb & La (Vacc)

Masking - ~~photoresist~~ worked one

Mounting - jigs not built yet

Aerofination - fast welds where the n-d of junction
Goldwelder - Al or Cu??

Jobs - new control system here this morning
control system looking good
side frequency out - new coil - coil has been built
tomorrow - another try

1/13/57 Policy meeting

1/13/58

(4)

Educational Summary

- 1. Blue Sky - 2 week group
short-term course - 4 people
- 2. Technician outside education
inside education
- 3. Formal education

Proposed that we have an orientation program -
reimburse 50% of expenses. Pass the course

Policy:

Working time

Costs:
Hodgson
H. 200
Pay ce
H. 200

Miner's bill:
Employee information

1/20/58

Policy meeting

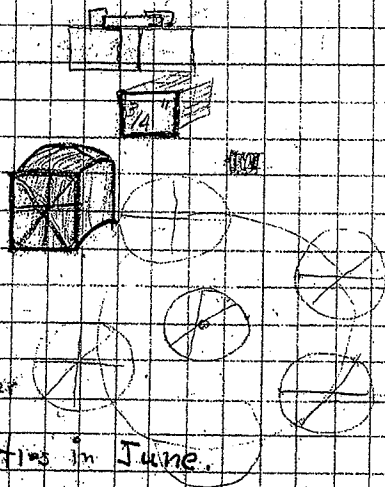
50-100 mc.

low power npr
php

Tom's Eng cost =

→ 50-100 mc ^{high core} low power npr } OR ?
switching transistors php } core driver

core driver - small Eng quantities in June.
1W 1000C.



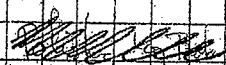
→ no spec sheets to anybody for a couple of months. ←

When head mixers
compressed air
pressurizing
clean up the lab.



25,000

250,000



Went to

are more concerned about timing than \$
we don't want to get out a limb

Chas Colvin - ~~is~~ director FCI
visiting

Went Colvin Labs

Adyson Wed.

Clean up this weekend **FRIDAY**

1/27/58 Policy meeting

143

Purchasing: had in 2 copies - 1 to purchasing
1 to project leader

\$5000 committee approved
2-5 range + 1
over 2000 - 2 people

up to 1K project leader
up to 450 Brown etc.

- Progress Reports - due monthly -

conversations with I.B.M.

new specs }
80 for }
40-2 rb }
30 (20 min) B }

100 in 6 mos
10,000 next year

- EQ committee -

2/3/58 Policy meeting

IBM ready to order 100 cye drivers @ 150-200 ea. 6 mo delivery
related info

Buy wanted based on - Signal Corps & CEI. want to see what we have done

Differen

JAH
DA
Pauls

Stinson & Greepelater

IBM
Murray
Brewer
Hayes
Parker

Report 109
110

new laptop #

to make decision on prep - after 10:00 to 11:00

Ed Baldwin

9 AM Thursday Technical Meeting -
~~()~~ - Joyce -

general information & coordination session
bottleneck session

see what

1 room N
P

20 room ? for back side diffusion
60 room P S

no terms coming thru from new on

last time
11 stockpile
9 row 100

Tom R. Corp 2/7/58

Jordan Journal Corp

Bill Johnson
in Rock Solid - take Physcom

... about R+D possibilities

PSI do ... with ...
Triple Diffusion oxide
marks

submit contract proposals -

B. Reid -

Spray - continuous system perhaps 10⁵/month something
pnp core driver & npn, pnp logic just like IBM

Arma - processing speed - 500 L life Reliability
guide cycle for Titia

Hycor Ester - nothing of interest

Qpsco - Boston - shift to qubits
core switch digital voltmeters

IBM Omega rise time in switching pulses
20 hse minimum - only baseline point
-70 to +100°C - \$200 - \$150 prefer pnp
we should weed out the bad ones

WADC pnpn + base load → only possible R+D memory

SWIC ALU ALU working on 20 group unit

Summary

get out samples to get out contracts

Tech Meeting 2/7/58

are problems now

what about β

what about a single metal for contact resistance

no wires soldered on leads

no metallized contacts yet

no high freq. measurements

flow sheets to follow process
to close circle

Staff meeting 2/10/58.

2/10/58 (47)

Baldwin here

Personnel requirements
Publicity items -

IBM Oswego quote is 2/8/58

open for n pn → p n p 6 mos. - \$150 for 100

current gain quarter low temp β_{min} 20 at -20

IBM will prob. need 2000-3000

Baldwin

Romo
Hughes etc }

sell our projects

β_{min} down
1/3 up

Giton

Sperry??

sketch

Electronic manual

BV_{CE0} 40V

P_c 100°C 1W

BV_{EB0} 2V

T_j 175°C

I_{cmax} 500ma

$I_{c0}(100°C) = 200ma \text{ max @ } V_{c0} = 30V$

h_{fe}

I_c 150ma V_c 10V 20

r_{bb}

I_c 50ma V_c 10V 40Ω

$f_{h\beta}$

I_c 150ma V_c 10V 80Mc

R_{cs}

$I_b = 10ma$ I_c 150ma 10-Ω

C_{ob}

I_c 10ma $V_c = 10V$ 30pf

EB → Electronic test gear for production needs emphasis

Bernie Elmiger → Electronic controls
automation test instrumentation

3-4 technicians
13.5 + 10% bonus

keep as stock out of production

2/10/58 cont'd

~~what~~ what does everybody think they should be doing

how much will production elect. test equipment cost
70-90,000

spend 100,000 in January

80,000 Household Improvements

evaluation report on 3-bowl printer

process ~~of~~ product manuals (Lalping)

Tech meeting

2/13/58

Problem areas:

diffusion exp
what about lifetimes
polishing necessary?

Mounting - Overheat: silver solder needs a flux
welder only go to 400°F - use pure tin.

Photoresist + Ag + Sn?

Welder meeting in order

Evap. cleanup - good h temp Bz outgassing

→ Welder won't hold us up at the moment

Silk screening - photoresist

Automation ducts photoresist - better
clean-up procedures
necessary??

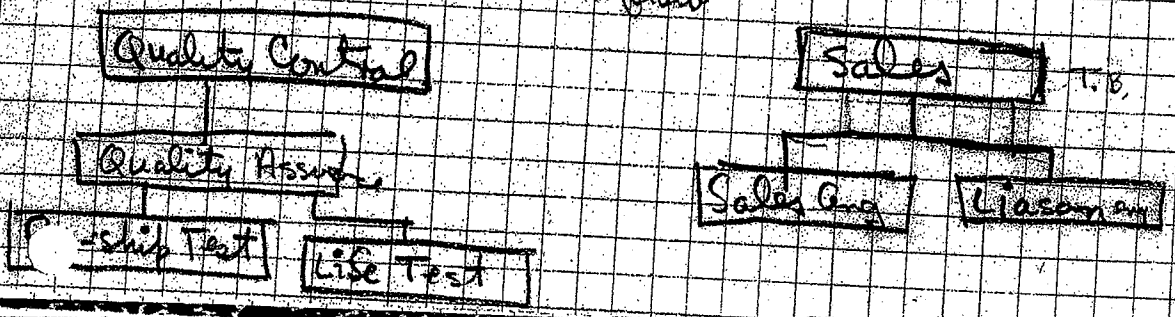
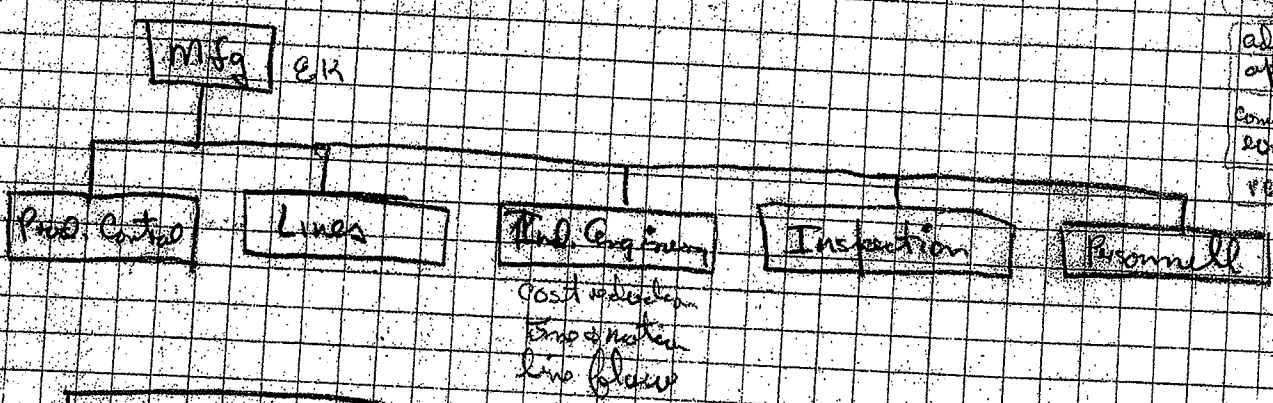
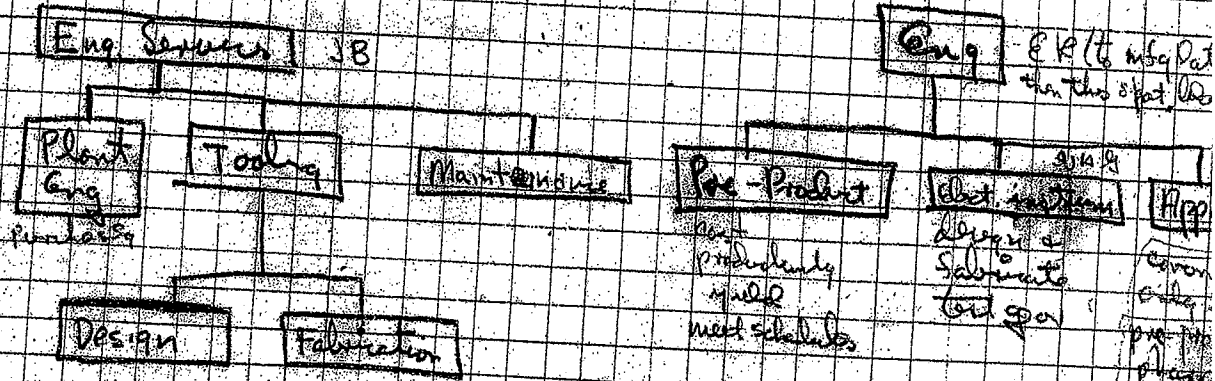
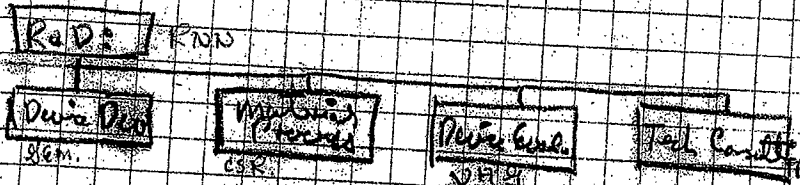
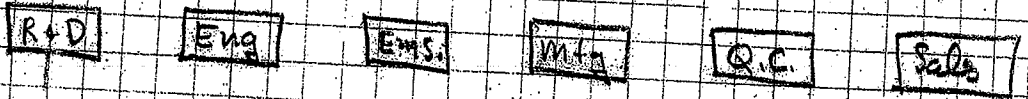
Testing - β 2 → 20 how much did base change?

I_{b0} 10 μ a at 60 V on paper

Hal situation improving

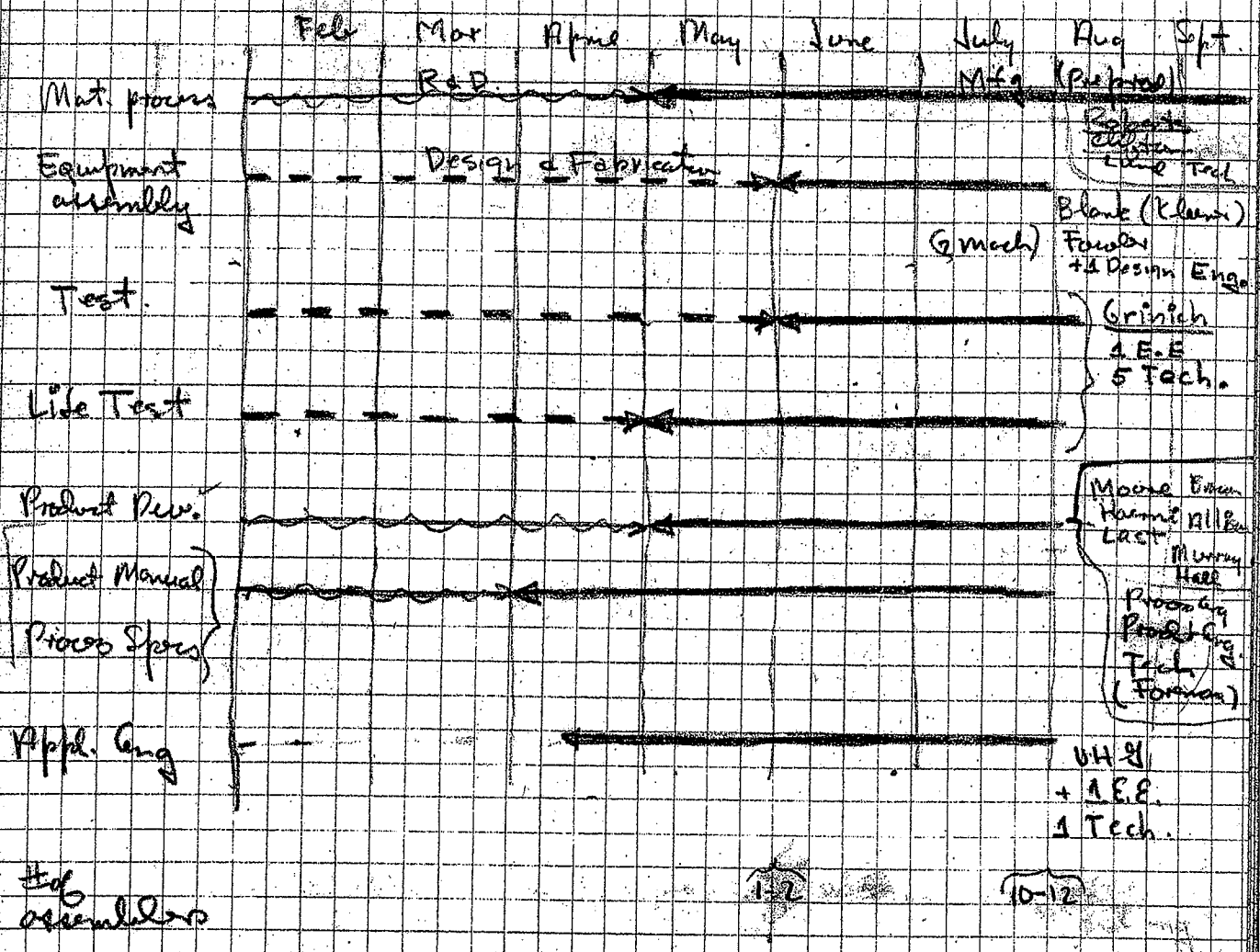
50 Staff meeting 2/17/58

Balance: Access. functions:



The above will take place in 6 months or so after first product

IBM 100 copies by Aug 1-58
we should have production rate of 1000-2000 Xlets/wk.
by this time 1000 low life test
about two months before August.



Additional investment for the most part.
the production equipment budget limit by \$100,000

SE RNM

Assume we have IBM Sercal - what do we add?

(Same thing - smaller geometry - logic transistor
low power high speed)

add identical Xistor NPN instead of PNP (or v. versa)

Follow
this
line

} back side diffusion - accurate doping

No
Major
Circuit
Changes

PNIP

Power Oscillator

PNP low Res
(NPN)

1 Amp PNP

High Power Heat Sinks 100's of watts

PNP } power switch

NPN }

PNPN 10⁺ amp

simple geometry

then interdigitation

spread the effort on interdigitation }
{ small geometry }

10W 100 mc.

Staff meeting

LA Trip: RNU

- Ramo - computer people
- Hughes - Culver city
- Hughes - ground systems
- Fairchild - pot. dev.
- Sydney - direct controls

Ramo - OK on downgraded specs.
have transistors almost everything (using GE mainly)
down on TI because of reliability (Phil's good)

Hughes Culver city - radar computers → 200-3000 transistors/machine
 1/4 Si because of low leakage
 1/4 mC clock. (mod freq)
 Direct coupled 0.3 μsec storage
 on current 10 mca
 want high DC p. hve.
 using GE
 Raytheon
 General Transistor
 all GE units

would like a pnp transistor as an output
(using a flip flop now)

{ airborne systems people need Si now
 { ground control people not so much

54 2/24 cont'd

Higher ground systems - bad audience

Hirshay - they want to TI select a get strong on reliability & variability

so they are shy on Si power

Fairchild Pat div. - they have stake table 60% thru audio
96 hour test -

welding & metallizing

System pushing specs look up

using 900A + In Transistor

→ β change from TI design to production

1/2 mic clock circuits

higher V_{CB}

$V_{CB} = 10V - 12V$ at $\sim 1/\mu A$

base-emitter voltage on on - .7 - .9 V.

10-20 mV collector

3.5

higher β (~ 30)

applications: reading & writing magnetic storage

one driver $\beta \sim 10$

pnpn thyristor to replace relays. 100ma \rightarrow 1amp

CB: ready market for our device with some slight increase in specs

we must get strong in reliability

free development samples in May.

2/24 cont'd (3)

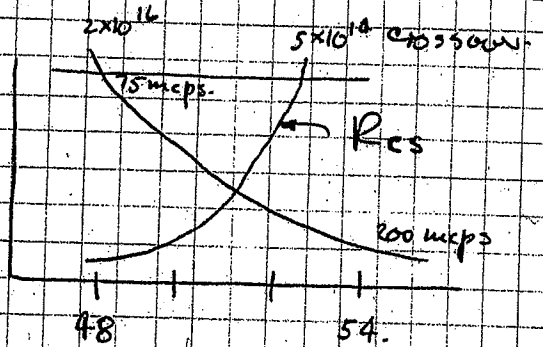
pre-production samples in July (at a price)

large scale production - end of the year.

Forecast of capital equipment requirements:

Prob intent - saturating circuits → lower a resistance DCTL

10^{20} in from back side C-30
 10^{18} in from front



Spec: $50 \pm 2 \mu$.

$C_0 \pm 2$.
back side

~~XXXXXXXXXXXX~~ pnp

we can sell the whole spectrum.

argument: units better but variable

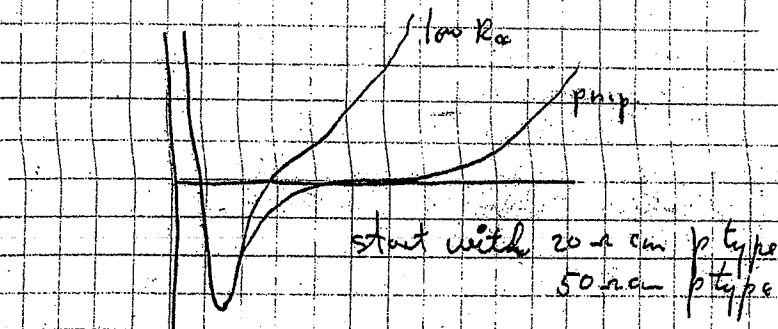
problem containment

make our downgraded spec transistor now.

put some effort on this - if this is in good shape by May 1 put this one in production

first device should be n/pn (reliability)
get p up.

worse than the pnp with back side diffusion



increase thickness 50 ± 2
 100 ± 4

EB: Conclusion:

Target NPN IBM Ourego with downgraded spec

	FEB	MAR	APRIL	MAY	JUNE	JULY	AUG
mach & equip (new)	3000	13,100	36,000	10,600	5600	4600	4200
mach & equip (use)	-	4000	3,000	-	-	-	-
equipment	5800	6100	5300	27,300	27,300	27,300	2,300
new estimate	$\Sigma 8800$	23,000	11,900	$\Sigma 31,900$			
mach & equip (new)	72,650	asap			$\Sigma 80,000$		
(no cash)							
to furniture lab	8,000						
laboratory equipment							
laboratory		10,000					
		$\Sigma 92,000$					

pre-product
(face samples)
2000/week

weld
evaporator
slide
thermal
already here

rocks
vibration
slide

Diff between old & new estimate = 12K.

start production
buildup here
to get to 20,000/week
200-300K

Income estimates for this year

July 1000 / week @ 25% yield

1/2 for life test

100 salable / week @ \$30-150 ea
avg = \$50

income \$5000 / week July $\Sigma = 20,000$

end of year 10,000 / week at a lower rate.

price down by 2x
yield up by 2x.

Aug 15K / week

increase 10K / month

5	July
15	Aug
25	Sept
35	Oct
45	Nov
55	Dec

to 200K

then up exponentially
in a few months

2.5 - 3 million sales next year in this device
if they are reliable

to get production going by end of year

2/27/58

Tech meeting

- sputtering over

headers 1000 of 4 types

3 composition leads

Kovar - glass - more reliable

→ Kovar header probably - hi temp solder to IKOF

make an own dies

Ag Sn 220°

LaRogue Signal Corps - Chief Safety Group

→ antenna etching

Photo resist in ill refute

emitter efficiency ??

to improve β

cleanup

go back to 1 or 2 cm material

(or even higher)

emit loss c - to 10^{11}

Estimated value emitter efficiency + lifetime degradation

3-3 at 10¹¹

3/2/58 Polym

(59)

membership on JETEC
EIA RETMA

JETEC 14W -

Tom Bay JETEC member

>Returns Vic Finis
Julia Black }

IBM Order line 00@150

W output at 70mc 900 good units

La Roque Swan 250mc 25°C 35% efficiency

\$500K back side diffusion
small geometry

La Roque line tomorrow

Yield: Final seal yield will be the number
used.

10AM Wed. Contract meeting

Budget AFU

2010 proposed budgets have to be split up.

Tech meeting March 6

Broad - 30% off - 70mc

pnp > 80mc only way to hit specs

$$\frac{r_b}{r_a}$$

$$r_{as} = 10 \Omega$$

Impurity profile within 5%

$$r_b = 735 \mu$$

$$\frac{N_A}{N_D} = 4$$

ii r_b now 100 Ω n/pn
3.3 μ base needed to get 80mc

pnp 20 Ω

n/pn 120 same geometry.

pnp β : base width 2 μ

$$\beta = 15 - 25$$

mobility
transit time

n/pn

$$3 \mu$$

$$\beta = 3 - 4$$

$$10^{19}$$

$$\beta = 8 - 10$$

$$10^{18}$$

$$\beta = 12$$

$$5 \times 10^{18}$$

N. plotting

we need 3 μ only

n/pn

pnp

$$f_{\beta} = 150$$

$$80$$

$$r_p = 100$$

$$40$$

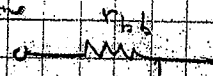
p-doped σ_{as} about 3 μ layers

62

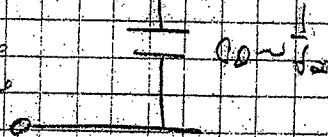
We need measurements

~~rise time~~ t_r

rise time



voltage
same



$t_r = r_{th} C_{out} \approx \frac{r_{th}}{f_{\alpha}}$ the important quantity

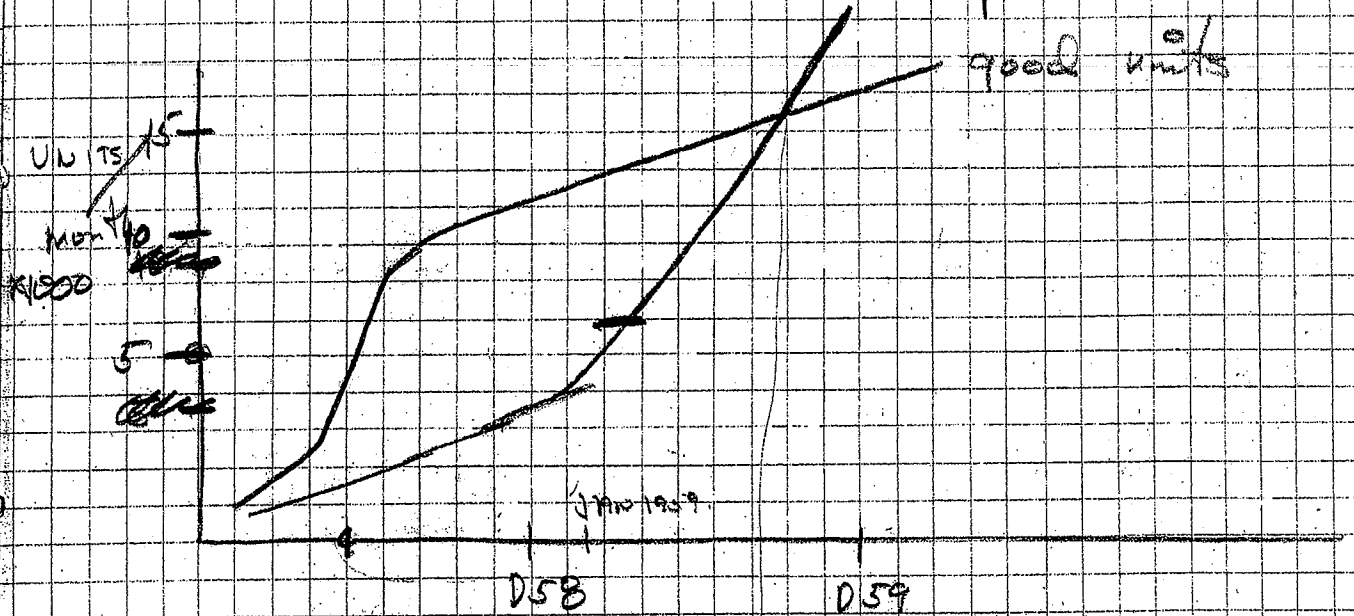
reballs

~~photon count~~

Palmy meeting 3/10/58

(68)

T.B. Estimated Sales Buildup



Aug-Sept 1958 Announce product(s) WESCON

selling as many as we can make.

This is a conservative sales growth
(probably will do better)

Unit price: Avg price ~ \$10

most sales growth exponentially
(price drops) sales volume doubles/year

Est sales volume '58 \$200K.

'59 \$900K.

Break-even on P&L middle of '59

1958 produce 23,600 good units
 3600 we keep for test
 2000 give away
 18000 available for sale

have 3-4 months inventory on hand.

(to get increased equipment to allow for increased sales)

EB - we should be able to double this sales picture

MARKET:	SRI late '56	predicted 1957 sales	3,000,000	Si trend
		1958	3,000,000	
		1959	19,000,000	

TI reported \$15,000,000 semiconductor 1957. out of total sales \$65M
 // ~ 1,000,000 units

- Transition - coming up -

~~2-3%~~ 2-3% of ~~the~~ turnover is conservative estimate

Hill Budget

MS

thru 1957	245,000	
thru 1958	957,000	+150,000 (new estimate)

~~out of money in 1958~~

total thru Feb #357,000

rest of 1958 = 1,000,000

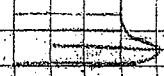
is out of money - end of 1958.

no room for second product till middle of 1959 on original budget.

Second facility? ~~60~~ 60-100,000 ft² = \$25/

firm decision on pnp - npr April ~~15~~ 15

Tech Staff meeting 3/13/58



design - V_{BE} are low by a factor of 4 300 → 75

What will npn - pnp - β be

n p n

2.2 μ base $\beta = 40-80$

650 Ω / \square
2450

instead of expected 3000 Ω

Co-op diffusion

Phos affects Ga diffusion

pushed in $\approx 2 \mu$

Xtal 59P

Chicago meeting

electrochemical potential, necessary.

p n p

Junction 2.2 μ . $\beta = 20^+$

1050
 $R_E = 700 \Omega$

Plan for npn - pnp decision

Set week beginning March 31 for production runs

Basis for judging - news -

20 wafers/batch - 5 batches in a week

- 7 batches of which 5 are chosen -

how thick?

250 wafers

we need vac bake out furnace + atmosphere around wafers

Mar 17

Mar 24

40/day =

- by Dec 1 handle 100/day -

Material situation

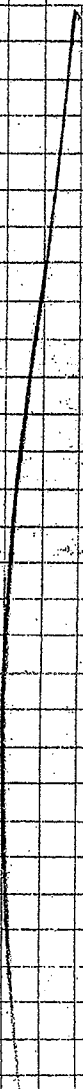
- S6 not desirable -

Phos	51P shorts	100
	58P good	111
	59P	

As now available for slicing

We need a resistivity spec for resistivity

- 2-1
- 2-0.5



March 30. Policy Meeting

GP Board meeting - go along with us this year -
 another board meeting - a couple of months & new facilities
 complete 1959 forecasts in a couple of months.
 quit contract?
 second product?
 costs for one product - O'Monnell for two

RUN. Electronics Industries Assoc. Meeting -
 Office of Sec. Res. ARDC. - Yost
 90% of work - big name at committee - fundamental work
 mechanism of diffusion

O.N.R. - some strong academic work - big name
 all on basis of unsolicited proposals.
 no interest in hardware at all

DOFC - Pathop

Signal Corps - Belmont - ^{Cherry}
 no money now for anything but
 contract continuation
 if they have money?

- ultra phenomena & solids
- photosensitivity
- fast temp transition - low noise
- linear & binary compounds
- SiF diodes
- solid energy converters
- new Si techniques
- parametric amplifiers
- Si perfection

it will take about a mos. to get money
out under contract

(new techniques - Si early in 1959 perhaps)

IBM - coming out here in 2-3 weeks
- Banning -

mean on silicon circuit parameters hard.
Talk over more reasonable reception specs

send us out test circuitry

London people - good complementary symmetry wanted

Philco } saturated circuitry
Sperry }

saturated vs non-saturated circuitry battle
Laird

Philco getting rid of non-essential resistances

Si alloy - emitter efficiency problems - @

JE - 3 lead pump - 200V / \$200 - no data sheet yet

non-tester

Sonsbeault - fluxless solder - work under contract on silicon
techniques

constant problems -

Equipment work request -

Tech Staff Meeting 4/3/58

1) npu work good contact meet pulse spec.
but not PC spec always - high R

2) Exp. RFE shelves

↓
npu Co

3) Smax low (best case in test of 300)

npu mounted board - high input impedance

30V - 5.0
50V - 5.0
70V - 10.0

51P - 5.0

58P - good high resistance material - badly damaged

59P - no shorts

64P - very bad shorts

71P - very bad shorts

Aligning
nose contact to pup nonchance
- bud balling



Policy meeting 4/7/58.

(73)

merit increases - 2% / 6 mos. normally 4-7% / year.

adjustment of increments on first go-around.

long adjustment scheme 1% of total payroll. → after 2 months

use 1/2% for merit increase total 2 1/2%

Dept heads decide how the pot is split up.

Review everybody in one day - April 30
Sept 30

Review everybody at once.

Advantage for accounting part of record
need to get comparisons at one time

Don't mention cost of living

Time is short by April 15th
mer raise \$10

\$25
\$25

Tech Meeting

4/10/58

Blay - problems.

9 AM Monday - allaying

2:00 Monday - PWP. WAD decision

Test Meeting 4/17/58.

(75)

Product Manuals

WED 10:15
New meeting date.

Atls, overlaten - CSIR

→ Saws & Jap JTE wab. to

Basic Design UHG
DA
JAH.

Diffusion JAH
DA

(w/10.15 - 10.15)

Photohoseing RUN
Mesaing JTE

Group Alloying } GEM.
Pipes } R.P.
Bridges }
Manufacturing }
Welding }

Test Procedures UHG
& Characteristics

FINISHED BY FIRST OF MAY

WEDNESDAY AM - PRODUCT MANUALS ROUGH DRAFT

3/8 / 1958

Policy Meeting:

4/21/58

Product planning 1958-1959 PNP

1 core driver - no production now
2 complement " " in the fall
what next?

PNP 3 terminal power switch
can make now except for packaging, up to 1000
up of specs.

small logic transistors
intrinsic barrier devices

high power transistors interdigitated
50A - 100 mil

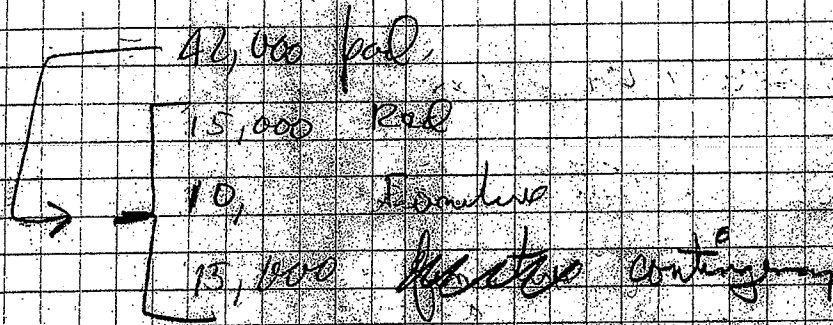
identical assembly to our core driver

Facilities - continuing research on design of power
high power packaging applications of pnp

study effort on various other devices -

15K for device 3 capital equipment

50,000	ReD cap equipment	expandable
95,000	Engineering	+ 15
5,000	Engineering	3,000
1,000	Sales	2,000



5000/month expendable equipment

now running about 8000/month

Max will work out forecast 3 month budget.

Personnel hiring - personnel request forms coming out

personal contact people - get resumes here first
 installation then personnel

Admin. department

Policy Meeting 5/5/58

New Numbering System

109-111 - still used for research.

100 → 200 in Org phase.

→ 300 heavy production

~~100-111~~

304 Materials Processing

New Job

new materials etc. (list)

Improved grinding techniques (Silicon) 105

Controlled oxidation (ppm)

Basic work on contacts (Change to ppm)

ppm triode

169 - Non allocated direct labor

Sick Leave

hardly - 6 days.

(Kor 59)

no pay for personal absence

prof 12 days

(E 101)

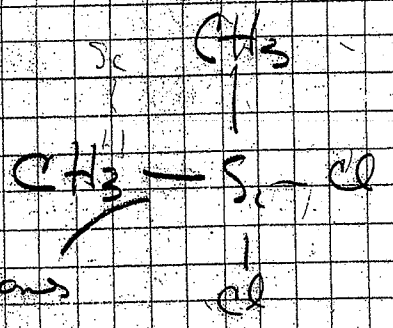
comb sick leave + personal leave

5/7/58

Report on Electrochemical Society Meeting, Clifton

High Surface Treatment:

- 1) moisture dew
 - 2) immerse into organo-silanes
 - 3) cure by heat & age
- 50% dimethyl dichlorosilane
50% methyl trichlorosilane



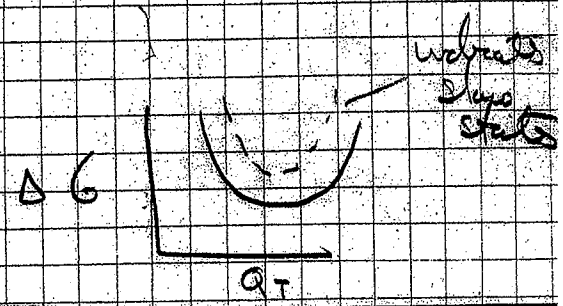
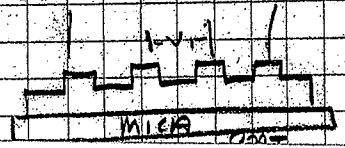
held 100°C for 1/2 hr
 250°C no effect a dew pops
 stand up into beds trichloro, etc

Walla - Bell

Surface stabilization by oxidation

1000°C high purity O₂ 10 min - several hrs
 Amorphous film -
 surface impurities to

- H₂
- O₂
- NH₃
- O₃



wafers yield
shorting
eng design on npr

CSR

Boron p vs length of (initial resistivity) $\left(\frac{k-9}{k-8} \right)$

{P}
{As}

(1.8, 1.6, 1.4, 1.3)

k=8
k=3.85

get 67 wafers P with 10% at 1.4
71 wafers As
1.4-1.0
Spec

so we will get 50-70 wafers at these specs
our wafers never cut in ~ 1.5 each
try to keep 5-10 specifications accepted ahead

PFA

8-10 wafers - Ga furnace flat but lubricate
5 on single flat boat

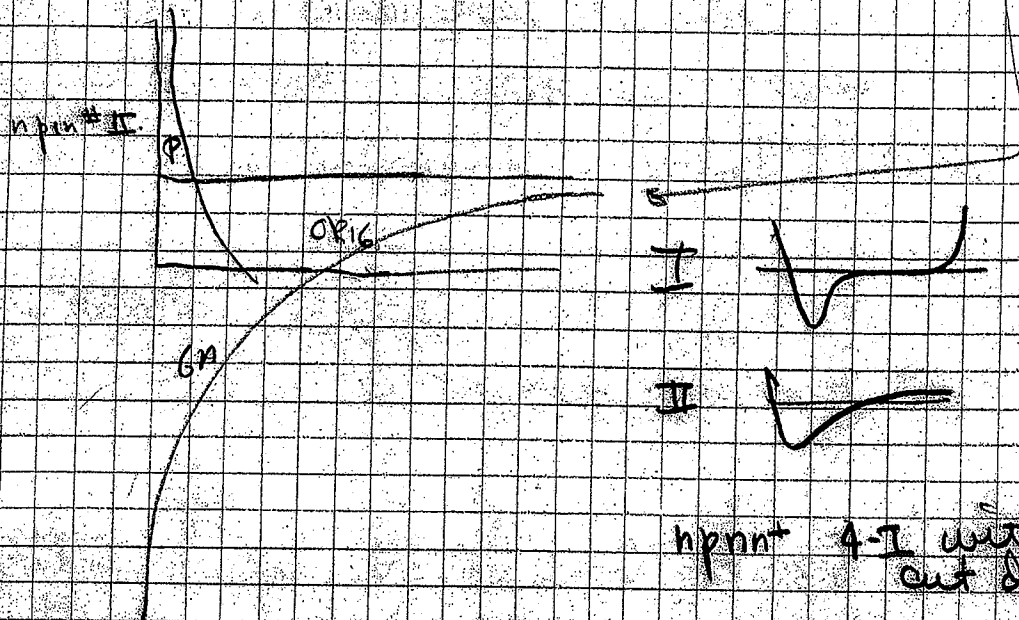
check the surface over on for as shorts go

Sto + Ga structure JAH prep to check structure
to to check locate cause of shorts - more detail -

Engineering changes on the npn

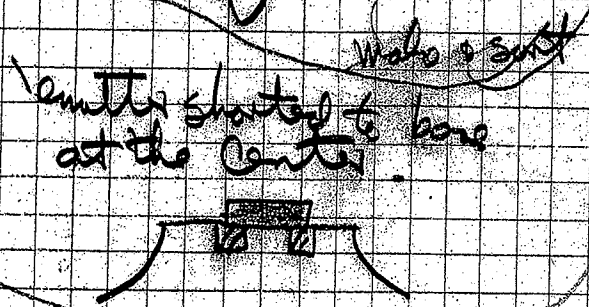
possible changes.

- 1) p n p
- 2) p n p n lamp
- 3) p n π n to get higher standoff & higher power
- 4) n p i n I
II backside diffusion
more efficient - compensation
- 5) n p n n⁺ Low V saturation



6) npn tetrapling triode

7) npn - diff



Advantages

complementary pair
not many pins around.

new area
made to go (electrical characteristics)
high voltage

new applications
military interest
HF oscillators

I low r_{e1}

II easier control of W -spread change

5) higher current capabilities
paired with $n_{pin} \neq 1$

Difficulties

contacts.

slowly developing market
non-ideal design not perfect
of n_{pin} low - this is
done prior to get high voltage

Not applicable to computer
power HF amp suited (have to go
to smaller geometry)

requires careful layout
long diffusion times
high r_{e1}

careful layout
long $\sqrt{D}t$

one of r_{e1} low
high r_{e2}

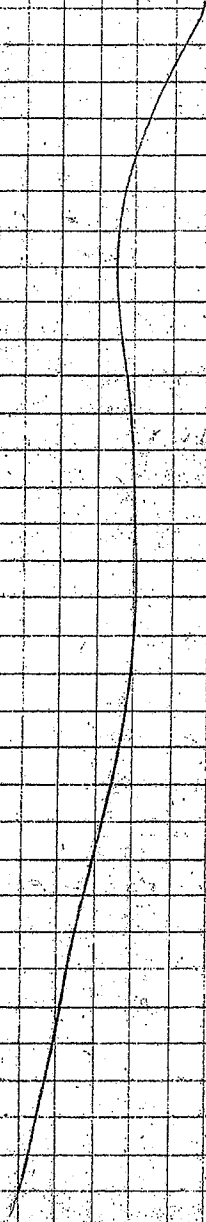
Single Fin

low β at low I

Easy - Flexibility

Tech meeting:

JTC educational meeting.



Wed meeting 5/21/58

Status reports

MEM - Transition yield Detroit

F.S. yield - 20%

Losses: Surfaces

rejecting on voltage > 1.5V

base

Problems

solder down with 4-5m

+ flux unsatisfactory

(Au solder down ready to
go next week)

not on final headers

Life test 20 going -

none failed in 4500 hours

Small Baker = 8m

~~Policy Meeting~~
POLICY MEETING - 5/27/58

Report on visits of Hodges Carter, Fairchild.

we have to get lag info. facility in operation at end of 1959
beginning of 1960

We have to get up to 100,000 units a week by end of 1959.

Three product building ~~at Fairchild~~

Units / week.

n pn 4000-6000 - week

pn p ~2000 / week

pn pn - pilot line

Was plant ready for occupancy April 1 - order to
meet growth rate.

End of 1959 -

n pn 30,000 / week

pn p 30,000

pn pn 30,000

total ~100,000

these are manufacturing numbers -

Yield will go from 20% → 70% by end of year n pn

25% → 65% by end of year pn p

25%

this will give us 60,000 devices salable / week by end of 1959

Cumulative number of units produced.

<u>end of 1959</u>	500,000	n.p.u	good units
	350,000	p.u.p	
	200,000	p.u.p.u.	

Use rule of thumb - 3-4 months inventory on hand

Sales lag by this time interval

Cumulative sales in \$

Assumptions n.p.u avg price \$20 this year 1958
 \$10-12 first half of 1959
 \$7.5 - 7.50 second " of 1959
 \$5 1960

n.p.p

same prices

p.u.p

\$20 first half of 1959
 \$10-12 second " " "
 \$5-6 1960

If these prices held, we should have accumulated

high figures
 2.8 million dollars
 1.4
 .8

low figures
 2.
 .9
 .7

6.8 million

3.5 million

by end of 1959.

96
Based on 200 transistors/assembly/week on a balanced line
Min of 80 ft²/assembly.

Assembler buildup 40 end of 1958
450 end of 1959. (2 shifts
max 250
at one time)

∴ we need $250 \times 80 = 20,000$ ft² for assembly
and test.

for supporting facilities we need ~ 30,000 ft².

Proc - prod.

PE

EI

SE

ES

Sales

Admin

Eng 12 = 15,000 ft²

Eng ser 10-12 ft²

Sales 2,000

Admin 3,000 ft²

Misc 50,000 5,000 ft²

Sales
Admin
Stores, etc

Cafeteria, lounge 5,000

Total: 55-57,000 square feet likely needed.

Assemblers \$290/month 180% overhead

monthly costs 30,000
 130,000 overhead
 200,000 salary payroll
 450,000 total operating expenses
 1,200,000 Monthly sales

Operating break even late 1959
 total expense break even spring of 1960

Family's total investment req. at max point
 \$3,500,000 including buying building
 This would add \$1,250,000

This does not include any sales money
 This does not include material either

How many professional people

applications engineers	7-10	administrative	7-8
instrumentation	4-5	technicians	
systems eng.	1-8	Design	6-8
proc. production	10	shop	8-10
Sales	10 - field		
quality control	4-5		
manufacturing	7-8		

90

∴ 100-150 professional people

This gives a total of 600-650 people by end of 1959.

50 R+D people half professional

Location - Center - go where cheapest - Arizona
max of 100,000 ft² per bldg union problems.

Stay away from area of aircraft indicators

Families like small towns

July 1 sites available

Redmond city north - nothing available

10 acres to
get
100,000 ft²

East Bay - Cahaba out for 100,000

Bahama - \$1/ft² lease only they like this

Stafford \$25,000 acre get financing

across street \$30,000 acre lease only

near Bayshore 50 feet of fill - \$9,000 acre
total

South Mt. View cheap but noisy

Sunnyvale - Keifer road \$9-12,000 acres

San Jose - too far away

San Mateo - no utilities but cheap.

Saratoga

Switching time

for going up
C_{in}

charge current vs time

$$t = \frac{Q}{I}$$

$$\Delta Q_T = Q_E + Q_B + Q_C$$

$$\Delta V_C = V_{BE(on)} + V_{BE(off)} + V_{CE}$$

$$\Delta V_{CE} = 2 V_{BE(on)} + V_{BE(off)} + V_{CE} + V_{CE}$$

$$\Delta V_{BE} = V_{BE(on)} + V_{BE(off)} \quad \text{only abs abs.}$$

$$Q_E = Q_{ED} + \frac{1}{2} (V_{BE(off)} I_E)$$

$$I_C \text{ (want)} = Q_B$$

to see

all charge comes thru base - *quasi* *static*

$$t = \frac{Q_T}{I_{BE}}$$

92

$$Q_c = f(I, V_c, V_{BE}, \beta)$$

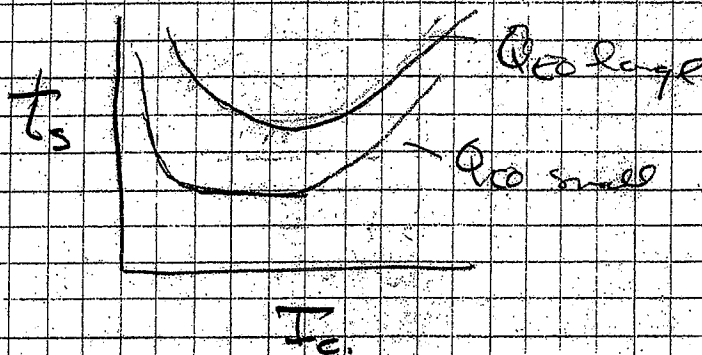
$$Q_b = f(I_c)$$

$$Q_E = C + f(V_{BE}, \beta)$$

$$I_B = I_c / \beta$$

$$t_s = N \left[\frac{Q_{EO} + f(V_c, I_c)}{I_c} \right]$$

$$t_s = N \left[\frac{Q_{EO} + A \left[\frac{I_c^{0.13}}{P^{1.13}} \right]}{I_c} \right]$$



DATA

P_c on limited to 1 W $N = 5$

I	T_c	T_{meas}
50	43	46
100	35	32
150	20	30
200	17	30
250	16	39

Res at high freq much higher than expected

Policy meeting 6/9/58

Forecast - equipment needs - up to 15,000 ^{rpm} engineering orders
15,000+ Mfg orders
to 30,000

same for other two products.
equipment & material.

R&D - RNN
Mfg - G
OSR, GR - materials

Required improvements - 55,000 ft²

Operating break down point - Sept 1959.

Wages	R&D	22	<u>January 1959</u>	Now use less 10-12
		26	<u>July 1959</u>	
		28	<u>Dec 1959</u>	

Total personnel.

total	184	Jan 1959.	Mfg. 63 50
	398	July	199
	638	Dec 1959	476

24

IBM requirements

300 Req this year \$150 each.

1500 Req end of the year \$75

3500 Req of 1st quarter 1959

20,000 End of 1959.

keep 3-4 months inventory

breakdown voltage
on voltage.

Req	\$ 20,000 / mo	material expense	Req	\$ 39,000
	\$ 29,500	" "		\$ 17,000
	\$ 27,000 / 3	" "		\$ 328,000

6/30/58

(95)

Report of Board Meeting:

Forecast to end of 1959 accepted

Spd \$209,000 over revised forecast

New facility - agreed - principle, but date not decided.

Rent more space 1000-1000 (at the end of the year)
(we people by the end of the year)

Committed to sales of 15,000-20,000 items
this year.

at avg price of \$40-50

Income expected \$500,000 - \$700,000 this year.

Will this pressure make us look bad - 1959?

Start carrying inventory August 1.

This could lead to a net operating profit - December!

O'Donnell

We can get architect's plans for \$5000.

Philips in 496 in trouble.

06

commitment from Owens 2000 on
through

mins of 40

to be delivered this year

Baro Newtons have required paper into circuit

letter talking 50,000

copy - Baro Newton

RCA at top of list 100 mc

will hit the market at the end of the year
sell for \$10 or so

Western 2039 → commercial

IBM has a contract with TI to build
Western 2039. -

our device at \$6-8 could compete to force
the market (Baro Newtons)

FAIRCHILD SEMICONDUCTOR CORPORATION

To: Management Group

Date: August 4, 1958

From: D. Miller

Subject: Organization Chart

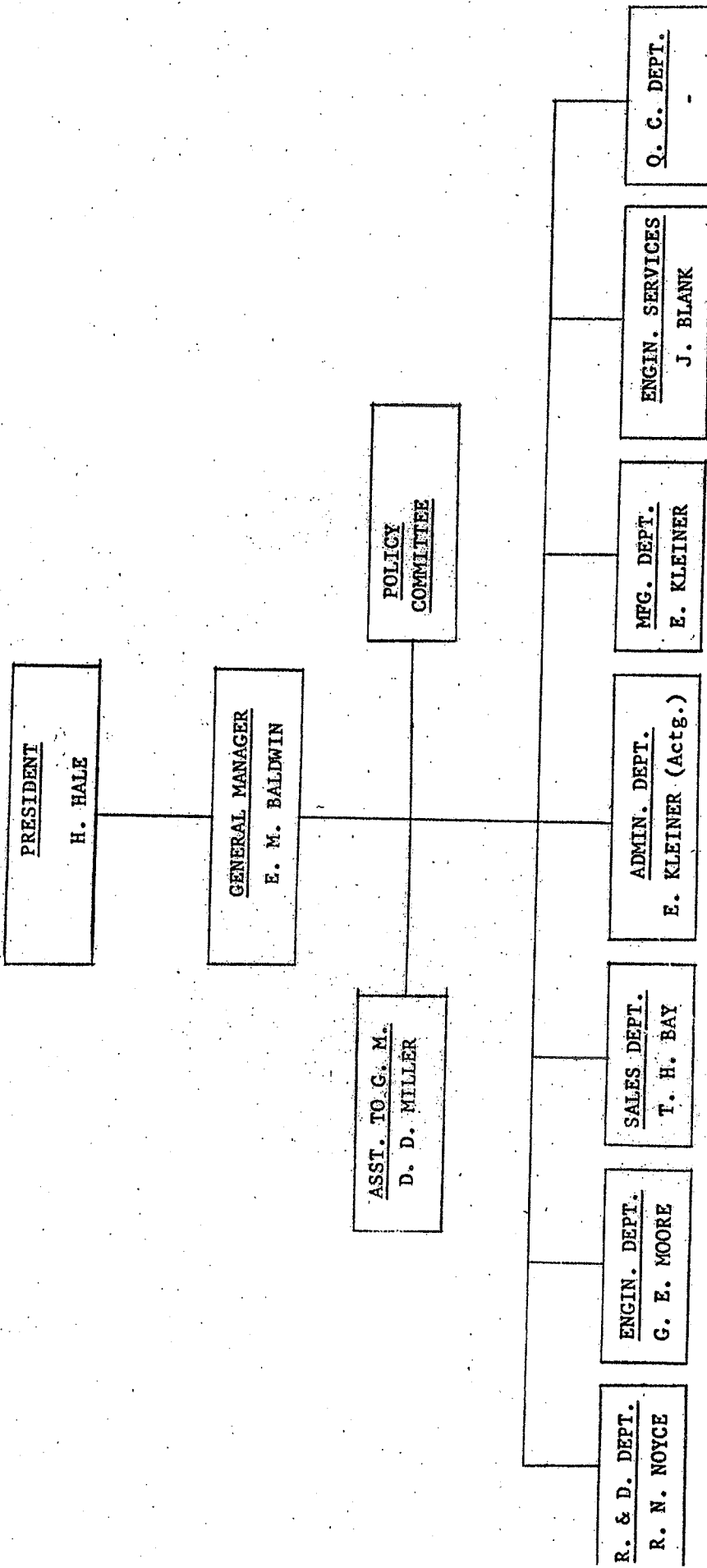
Copies: All Supervision, M/F

Enclosed are organizational charts for each department. It should be noted that these charts are tailored to our current organization, arrived at by discussions with each department manager, and the general manager, and do not include a sectional breakdown for those areas which will be staffed at a later date.

The organizational charts will be revised at periodic intervals, and will incorporate any additions or changes to each department chart.

DM:gb

D. Miller



RESEARCH AND DEVELOPMENT
R. N. NOYCE

MATERIALS PROCESSING
C. S. ROBERTS

SOLID STATE PHYSICS
J. A. HOERNI

DEVICE RESEARCH
J. T. LAST

DEVICE DEVELOPMENT
R. N. NOYCE (Actg.)

DEVICE EVALUATION
V. H. GRINICH

PROFESSIONAL

- 1. J. Clifton

TECHNICIAN

- 1. G. Barber
- 2. T. Bright *
- 3. L. Lunn *
- 4. B. Person *

PROFESSIONAL

- 1. P. Flint
- 2. T. Sanders

TECHNICIAN

- 1. P. Hinchcliffe

PROFESSIONAL

- 1. D. Allison
- 2. R. Craig

TECHNICIAN

- 1. C. Gunter
- 2. P. King

PROFESSIONAL

- 1. I. Haas
- 2. G. Reddi

TECHNICIAN

- 1. M. Siegel

* Currently performing material processing operation.

ENGINEERING DEPARTMENT
G. E. MOORE

PRE-PRODUCTION
D. R. WEINDORF

APPLICATION ENGIN.
V. H. GRINICH

ELECTRONIC INSTR.
B. ELBINGER

PROFESSIONAL

1. R. Brown
2. L. Carlson
3. J. Nebozuk
4. C. Plough

PROFESSIONAL

1. R. Beeson
2. B. Black
3. M. Desai
4. R. Kikoshima

FOREMAN

1. E. Beauchamp

TECHNICIAN

1. N. Kanawyer
2. M. Peterhans

FOREMAN AND TECHNICIAN

1. W. Allen
2. J. Carnahan
3. R. Hall
4. P. King
5. R. Parker
6. R. Robson
7. R. Vander Veen

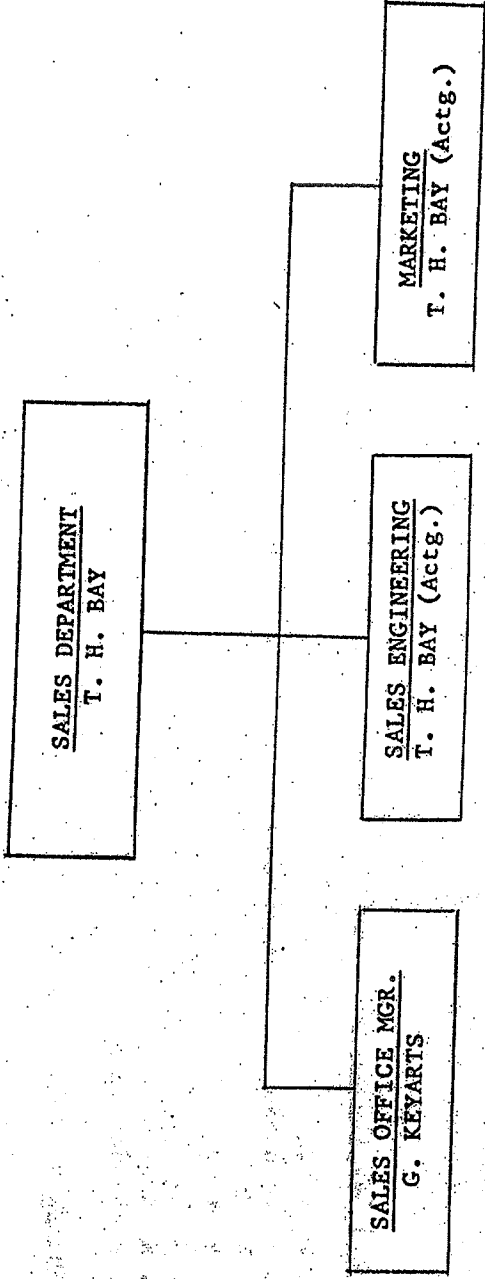
TECHNICIAN

1. G. Allen
2. D. Ferris
3. E. Held

ASSEMBLER *

1. P. Burch
2. M. Campbell
3. M. Crowder
4. A. Ferguson
5. A. Holt
6. M. Patkus
7. V. Smithee
8. J. Sopko
9. P. Sarantopoulos

* Current in Jan 1964



EASTERN SALES

I. H. Bobb

ENGIN. SERVICES DEPT.
J. BLANK

PLANT ENGIN.
J. BLANK (Actg.)

MAINT. - MECH.

- 1. C. Haley
- 2. C. Jodocy

CLERK-SHIP. & RECEIV.

- 1. P. Peeters
- 2. O. Walker

JANITOR

- 1. J. Johnson
- 2. G. Langevin

TOOLING
J. BLANK (Actg.)

TOOLING DESIGN
L. KOSS

DRAFTSMAN

- 1. W. Busche

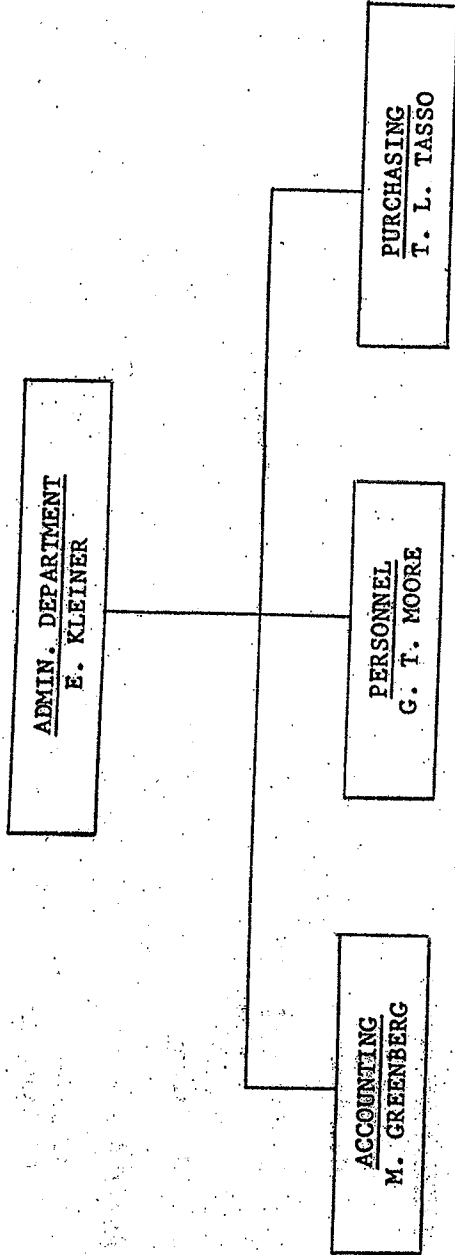
TOOLING FABR.
E. TROYER (Actg.)

SHOP FOREMAN

- 1. E. Troyer

MACHINIST

- 1. S. Chapman
- 2. H. Lawler



BOOKKEEPER

- 1: L. Tibbs

INTERVIEWER

- 1. C. Heineman * (Actg.)

CLERK-TYPIST

- 1. M. Hrynczak

SECRETARIAL

- 1. G. Baker
- 2. C. Heineman *
- 3. M. Weis

Actions

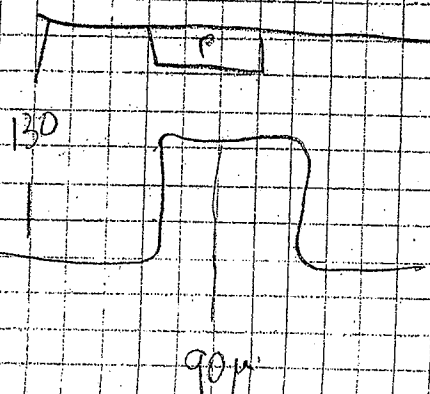
- 1. Resistance Growth
- 2. Intermetallics
- 3. NPN 50% OPA all 150m
- 4. PNP
- 5. PNPN
- 6. Backside (Diffusion, Alloying, Etching)

Li etching
 IR Transmission
 Impurity Reduction

Start

- 1. p wave diode pit alloy (100)
- 2. Small geometry - pull away

Autonomy furnace being set up for high doping



p^{23} gradient
 1.5µm
 area 10⁻⁵ 10⁻⁴ cm²

NaOH etch

Ransom - Acta Met.
 selective etch

Put alloy
straight mesa.
Wells method.

March 1

— good logic unit - small geometry

CSR - InSb - zoning
(GaAs) "

① Get decent InSb crystals

② the work on GaAs systems has been horizontal
growing - a graph to best
closed system. Control of
partial pressures a separate
process
reaction between Cu & As

→ Phillips Res reports

8/25/58

Polin - info meeting -
(Calif group + Walt English)

RUP - Western Show -

big interest at booth - from competitors as well
we scooped the industry - nobody ready to put
something like the market 2N560 Bell closest
competitor - No prospect of anybody getting our way
in the immediate future.

transition

EK - Personnel situation

Hughes - PSI in bad shape morale-wise

Mote coming up from PSI

Instruments still a problem

O'Keefe coming - Philco output

Ashmore - Application engineer

best response from D&T mos - Electronic news

Boq

Sales picture

Response extremely gratifying at show

Electronic Equipment Ad - 467 responses
ad went out 8/10 + 30 letters & telegrams
within first 10 days

Requests for quotes for sample quote

order for 500 IBM - Poughkeepsie

Bob - 200-500 Sperry orders this week
200-500 Anna
700 GE-Utica E=1000-2000
(" ?) Butterfield

100

Ham Production

up above 1000 final seals/week for the first time

process in operation 70 wafers/day

10 final seals/wafer = 700/day

several hundred a day. 2500 this week.

big kind will occur on testing

yield jumped to 37%

Bay (cont'd)

total # of inquiries ~ 1000 all told.

Bevin - IBM Omega - will order at least 2000-3000 today

open orders now - 550

shipped ~ 250-275

expected orders 5000-6000

"we can sell the 15000 units we expect to make this year without any trouble"

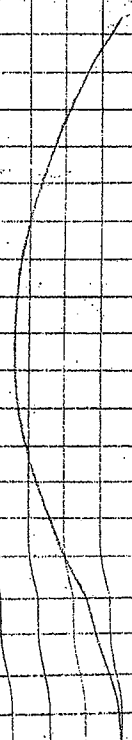
unit price will probably hold up to 90-50 up thru December

Booked - date	262	\$ 36,000
on order	590	\$ 28,000

July Book - cost estimate on new bldg - 415 ft² with primary distribution, air conditioning

Time scale on bldg - 9 months from initiation shaved a month or so.

$$\begin{array}{r} 15 \\ 10 \\ \hline 15,000 \\ 3 \\ \hline 45,000 \\ 10 \\ \hline 75,000 \end{array}$$



pnp status meeting:

VPH
RUN
VH6
GEM
HTL

wafers - 0.6-0.7- μ material (grown to thickness of 0.6-1.1)
(npr creep up to 2 μ - still getting IV sat. res.)

Base diffusion in poor shape - (S_b ~~inadequate~~)
inadequate

not consistent thru
all wafers in run.

$V/I = 10-20$ μ function

should be higher for
 R_p, C_p present

the problem is probably
alloying or factors R_p, C_p give

as of this
week

As being tried to see if doping is more homogeneous
for alloying - As will show in sequence later than S_b
(CSG)

Emitter diffusion not giving any trouble (Barn)

$V/I = 0.5 - 0.6$

3.5	1
2.8	0

2.5 gives pits
3.1 gives lower V/I

As, Oxygen, nitrogen - others

Nickel - electroless plate which is lapped off -
a - lap off base layer and then lower diff. re -
evaporate nickel

Front side - evaporate Al-Sn-Pb. (critical alloying - more than
5 minutes base voltage
becomes worse.
less than 3 min - no alloying
at 580°C)

- this holds voltage low during assembly ratio few 10/10. -
do some probing

Gen - points on opposite side of base by 3-2
gold balls " " " " " " 1-2

(photoresist will hold up to A_{Sn} alloying temp R.M.)

work with Au-Sb furnace

Backside

1) lap off backside (to 80 μ thick)

wrap aluminum

alloy while front side is alloyed (restricts alloying
time to 3 min at 580)

solder with Au-Cu 10% made by C.S.R.

(Shot spheres ordered from Alpha)

R_{set} 1-1.8V

some switching between 400-500 mils

oxide layer
~15 μ

104

2) evap a heavy layer of Au on Lockshield
disc
solder directly
switches at about as 1)

3) evap Aluminium
use Zn as solder (melts at 690°K)
gives 1V sat voltage.
very easy to solder.

4) keep lower layer
solder with Au-Co gives best
sat voltage

~~etch~~
etch sample wafers - evap before
1. ~~etch~~
2. HF.

etch
acid wash (etch)

5) 5% Sn 95% Pb.

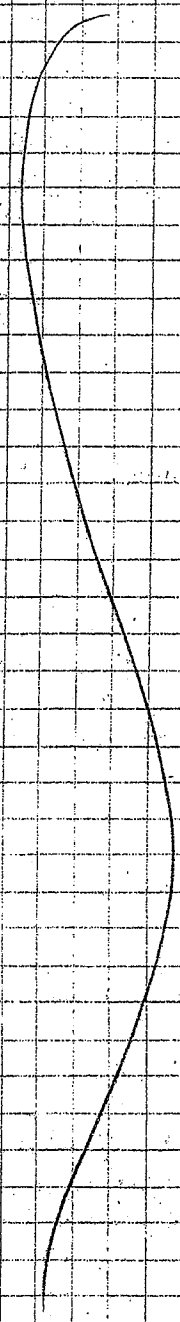
6) to try evap Au - Au on heavily
pressure weld at 250°C

9/6/77

try photo-etch

What are Target Characteristics?
3 pins

all PC parameters should be as close as 4 pin
base voltage down to 4 pin (disturbance)



9/15/58

R&D Meeting

Patents

Description of Invention - what is new, what advantages
Description of Applications

Patentable Ideas:

Single metal contact (?) BTL using
we used thin at pretty satisfactory
claim on another patent.

automatic
indexing

Selective plating,
pullaway techniques etc. CSE

[John Rolls - Lippincott & Smith - proposed patent attorney]

[A method of machining by use of a gaseous etch
Burr pits]

[Diode with oxide overlap
collector only under emitter]

IAH



[Thick base PNPN - voltage drop is limited by
conductivity modulation]

[shunted base-emitter PNPN - non-saturating
= Terminal]

[Turn off pnpn with a pulse WJH]

No plating for n-type diffusion, leading to diodes

watch on p-n junctions - fill as soon as possible

Status reports

JAH - 10 Ω cm - no input, contact
various soldering techniques
good directly to Si trench

UHQ pnp - evaluate switching times
pnp - switching times comp to npn, lower storage time
small gain pnp PNC 1000-1500

CSR full-wave envelopes
multi-metal-mimicible liquids
preferential plating (chromium)
Silver & Ru

crystals - can grow 10 μ 2 rods
reproducibility, control - good shape

get out good In Sb -
then GaAs - (1.2)

JK - Resistor grown - no reproducibility, get
lifetime - good shape

PTC - reports a collector junction
solid elements in solder junction
phys characteristics - switching, lifetime, etc.
low continuous - wetting of surface with die.

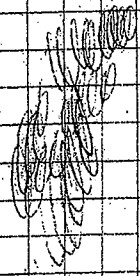
2A - deep fracture problems - p too high low grain size
width - surface problems
if base metal is removed here is not good enough

phos diffusion 1100 \rightarrow 1200 to get a reasonable
time
the rate p is iteratively a well.

systems coming in again recently.

How of oxidation - there is diffusion
just thick enough oxide layer

1/4 inch slotted (9 fingers)
this will be continued -



Write progress reports on the first -
have this meeting on 10th - 15th.

- get a line furnace - set up service

POLICY MEETING

9/18/58

109

NEW BUILDING - SAN JOSE

put as much possible into ~~new~~ leasehold improvements in 5 year period.

Price limit, \$750,000 plant
250,000 leasehold improvements

62,000 sq ft. (90 to 100,000 sq ft. of 1960)

110

Sept 29

Policy Meeting

Body Location - Mt. View

Oct 6

Bay
Allica
Johnson
Moore
Cushman
Key
Parker

~~10/10~~

RCA MA 1863

$P_c = 2W @ 23^\circ C case, I_{cmax} = 50 ma$

n/br.

next saturated bias

	Min.	Typ	Max.	
R_{cs}	8	12	20 Ω	
h_{fe}	0.8	1.5		$f = 100 mc, V_c = 20V, I_c = 5 ma$
$r_{bb} \cdot C_c$		35	130 μs	
70 Mc β_c	13	17 db		$V_c = 30V, I_c = optimum$
C_{ob}	0.4	0.8	162 μf	$V_c = 20V$
$t_r \cdot t_s$	$I_c = 20 ma$		3 to 5 μs	

price now 460⁰⁰
June 1959 8⁰⁰

~~5x10 mil mesa probably~~

VRG - How is the point in trying to level the current limitations for the panel as we current limitations?

TP 21 338
Photo 496 - out of focus limited in size

11/9/58

Report on Ottawa Electronics Meeting CSR
DFA

Westinghouse spends \$2,000,000/year on semiconductors
 JE 1,000,000

Emphasis on power generators.

Ref. of papers of most still 5 times too low.

For power generator: $M = \frac{\bar{F} \alpha^2}{4k\rho}$

$$\alpha = 200 \mu\text{V}/^\circ\text{C}$$

$$k \leq 10^{-2} \text{ watt/in}^2$$

$$\rho \sim 200 \text{ mho/cm}$$

Mooser - Short range order the important one for
 semiconductivity - long range order
 for specific crystal structure.

10/16/58

113

R&P meeting

Wilson	Reback	Chilton	JTL
Hirsch	Wesley	Reddi	Waring
Kami	Haas	Wesley	

5 million units

Swan 100 → 250
30% gain 10 → 30 lbs

low β units
switch time fairly high

low β units 6-9 lbs

10% gain

high β - lifetime - base controlled

high β high cutoff - ~~units~~

β = 1/3

switch eff = cross factor of 1/10

$$f_c \sim \frac{1}{\omega \beta}$$

WW

124

Policy meeting

Day 10 - Europe

Siemens

Mullard (sub. of Phillips)

Diodes selling for 25¢ [produced here for 35-40¢
sell for 50¢]

assembly done very well - sigs & sockets excellent
Diode sockets

nothing much of interest for us to sell
few diodes perhaps

all sell

no pressure to go to SI - dealing with a
subcontract market.

poss. of selling wafers for mounting

Mullard. Res. Lab.

Trus - Dr. Reinhardt

Hoslett - no semiconductor work

po. Diodes being made

sample of AC 170 - 470ms cutoff He

Gilbert & Linsdell - Home

Mullard or supply us with 100,000
200,000 units
for resale
Cost to us \$3

ult cost Si 20% >

power x 100 25-30 \$/
22-13 \$

heavy aid [135
[75

Surveys 15

Si alloy 100

Others 195

Southampton -

packages are non-std packages.
could be put in air packaging

Result - interpreted actually as a
incubating arrangement.

coming here - April

16 Small Geometry Meeting

VHG
JAH

DFA
GEM

JH
JTE

RNN

	Motorola λ_c	UHF λ_c	Material
	2N695 Switch	2N559	2N700 UHF
BV _{CEO}	12		30
BV _{CEB}	15	25 (100µs)	30
BV _{CEB}	3 (100µs)	6 (100µs)	0.5

Phase L-f

R_{cs}

25 (10/1)

22 (10/4)

C_{ob}

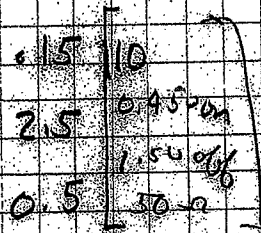
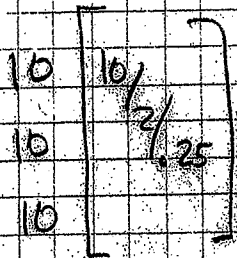
4 (6)

0.8

r_b

50 (700µs
2.6)

t_{dr}



t_s

t_s

25 M/sec pulse width

width
5µm

f_{max}

600µm (2)

A_p

12db (200µm
7.5)

C_{Te}

Phil 2N501
9/10

FSC Present
X1040c

12 ← BU_{ces}

30

15

60

2

5

4.5 (2, 5, 20ms)

10 [5ma, 10V
20ms]

20 (10/1) max

20 [10/1]
40 [10/2]

5 (1/3) max

1 [10V]

I_{pp}	max	[25ma / 2.5 1.05V _{dbb}]
9	18	
9	12	
7	10	

8 t_d
18 t_r

300-700

30db @ 100mc
calc

7 pf @ 0.5u

Small Geometry Objectives Specs etc.

UHG
GEM
A
DFA
JTL

specs - measuring program

→ BV_{CBO} 30 V MIN. Design ⁵⁰ 60V 0.5 μ m
 lower resistivity - less surface breakdown limits
 total area of surface
 100 μ A 30V
 50% range of static resistivity.

→ BV_{EBO} ~~3-3 V~~ 3 V 5V Design
 100 μ A

→ $LIV_{CER} = ?$ $f(BV_{CBO} \beta) \approx 20V$
 Limiting voltage rises base between emitter and base
 (asymptotic voltage) $10 \Omega = R$
 $50 \mu A$
 $I = 25 \text{ mA}$

→ $h_{FE} (10 \text{ mA}, 0.6V) \gg 20$

→ $h_{FE} (50 \text{ mA}, 0.6V) \gg ?$

→ $V_{BE \text{ sat}} (10 \text{ mA}, 1 \text{ mA}) \leq 0.9V?$

→ $V_{CE \text{ sat}} (10 \text{ mA}, 1 \text{ mA}) \leq 0.5V$

120

→ $I_{CEO} (15V) \leq 0.1 \mu A$

→ $h_{fe} (20mA, 10mA, 10V) > 10$ $V_{CE} = 15$

→ $C_{OB} (10V) \leq 5 pF$

Switching times

Circuit 2N301 Philips He
railway

$I_0 = 10 mA$

$I_{B1} = 0.6 mA$

$I_{B2} = 0.04 mA$

turn on

turn off

Design
criteria

$t_D = 50 \mu sec$

$t_R = 150 \mu sec$

$t_S = 150 \mu sec$

$t_F = 65 \mu sec$

Philips Application note 330

Circuit $\beta = \frac{I_C}{I_{B2}}$

data is paramount!!

f_{max} - don't specify (100 MHz)

power gain - take what comes.

Bob Benson - Measurements.

Mr at 0.5 sq-cm

4 fringe base 80%

shallowness - to prevent penetration

8 fringe matter (duant. 3)

4 fringe base

122

Au diffused 2N696 \equiv X 4100

X 4100 Au diffused 1.030 mil collector
0.15 mil emitter

F 4000 diffusion recipe
 $\rho = 0.5 \text{ cm}^2$

set of compatible specs needed - compare with 2N560

aim to hit low current switching specs.

try to meet Buships 2N560 spec change # 5.

$$I_c = 10 \text{ ma} \quad I_{B1} = 0.5 \text{ ma} \quad I_{B2} = 1.5 \text{ ma}$$

$$t_s + t_f = 250 \text{ nsec max.}$$

but we make ARMA sep LC of spec?

$$t_d + t_r = 0.65 \text{ } \mu\text{sec.}$$

$$I_c = 3 \text{ ma} \\ I_{B1} = 0.2 \text{ ma}$$

we have to worry about $\beta, k, d,$
high level unit

Arma WTC - M320 - 218

$$BV_{CES} = 40 \text{ V}$$

design cat 80 ~ collector base transition
design 80?

$$t_d + t_r$$

f_{cs}

20 μA @ 40ma

design cat 10a at 10ma

(1)

K $t_d + t_r = 400 \text{ ns}$

$I_C = 40 \text{ mA}$
 $V_{CE} = 12 \text{ V}$
 $I_{B1} = 2 \text{ mA}$

L $t_s + t_f = 1.8 \mu\text{s}$

$I_{C1} = 3 \text{ mA}$
 $V_{CE} = 12 \text{ V}$
 $I_{B1} = 0.1 \text{ mA}$
 $I_{B2} = 0.6 \text{ mA}$

we must meet our switching time specs. 100% so we
don't have to test

we want to make:

K: 300 ns
L: 400 ns

we technique as std test fixture

Measurements?

Arma X¹⁵ meeting Thurs 1/10

JAH $\rho = 0.60 \pm .15 \text{ } \Omega\text{cm}$

no change to emitter prep.

No Nickel plating

Somewhat slower emitter diffusion

Remove oxide on both side of wafers.

Evaporate Au [is this critical?]

~~the diffusion~~ x 3" of 0.015" wire

Au diffused in O₂ 970° for 20 minutes (or more)

Standard from this point on.

Die sort - lower breakdown voltage. 20
10
1000
New final test spec.

we want 20 good devices from each test run.

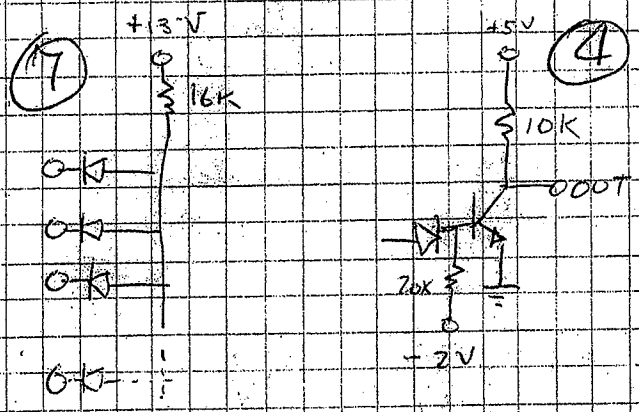
Ⓢ Omit everything after final seal.

Optimize: Initial ~~diffusion~~ resistivity
Ni diffusion
Emitter diffusion

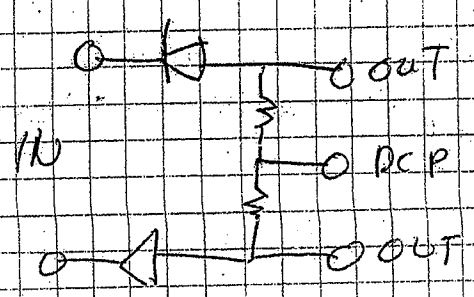
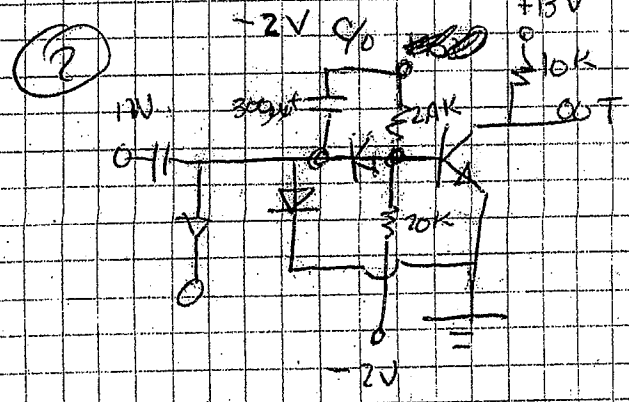
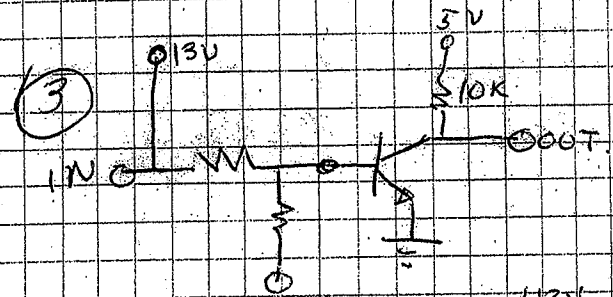
Arma - KASJIAN -

Microminic Circuits

Full adder Built from dig computers



Microminic
Circuits



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atomic people decide how many elements/wafer

"Volumetric efficiency" ~~is~~

of external connections neces for steady process

Decreases reliability

4-5 wafers seem to be optimum.

altogether 9 resistors

37 diodes

send us plates with resistors, capacitors on the plate - we put on diodes + surface contacts

~~III~~

hole diam 0.1"

Diodes: Capacitors $3\% \pm 25\%$

Diodes back to back.

Diodes now used.

~~1N658~~

1N658

Pdco Receptor

1N663

PST

or.

Resistors $\pm 10\%$

Diode specs

100k a in 0.3 use from 5ma to -40V
this can be reduced

Diodes COMMON

Circuit clock freq 130 Kc

QUANTITY: 20 sets of wafers to make
20 addrs
2 or 4 ~~sets~~ sets to us

Quote ASAP

Transition.

Cost

supply a inert semiconductor

37 diodes

a X1500 / addr

Cost / addr

also surface protection ideas
pne inch / without protection

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Xistor min β 15-20

$V_B > 20V$

I_{C0}

$I_C = 1mA$

$I_{B1} = 2.5mA$

off $\approx 1 \mu sec$

$I_{B2} = 0.2mA$

~~126~~

Eng Charge Board

Meeting Time - Thurs 10³⁰

Quorum:

Mfg
Eng -
Sustaining Engineering

Emergency Contact

120

Arma

2/4/59

discrete
new list of spec (to be issued)

150 ma spec. BUCEP 10ma 25 V

90V

LUCER 25V.

150 max.

1.5V

3.5

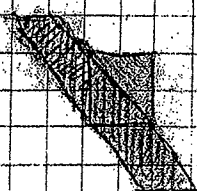
C_c

30 pf

Max 50 pf

I_{cbo}

.01



$t_{st} t_f$

150 nsec max

t_s 100 nsec

$t_s = 50$

Bell Lab 3/4 amp core Jucor 2081

total switch 250 nsec

replaced at Wash meeting

what is turn off?

V_{sat} 0.4V

6 Ω

C_c < 30 pf 5V

BUCEP 25V

turn on 50-100 nsec.



Resistance: 0.6-0.8 Ω ?

we have met three objectives spec already -

$\frac{K+1}{2}$ spec

low current R_{on} spec
high current spec

→ high ρ
→ low ρ

ρ 5
0.8
1.7

flu 97.5° - 1050°

we are better by a factor of 2

V_{GS} sat on

0.5 Ω em meets 54100 by spec

$t_s + t_f = 100$ nsec

(45+55)

spread

118
88
19
8.5

g & h (low current spec)

1.65 μ sec spec

spread

2.0 μ sec
1.23 μ sec

~~1~~ 10 nsec base

$t_s + t_f$

1.650 nsec

K+L OK!

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Report on Eastern Trip Wayne, Hirsch, et al
S.S. Circuits Conf. Feb 15 -

core current don't buy any thing
small memory size
2N 05 112

Hughes Ge 75KMC

100 bit shift register - temp storage.

White diodes - Ambient sensitive as
far as Q is concerned
at 100 μ a sec.

new 2N560

1060 ?

V_{cc} 25 μ

16 pF.

Johnson - why not use field effect trans
see Abstracts

20 1012

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Western 2N1072

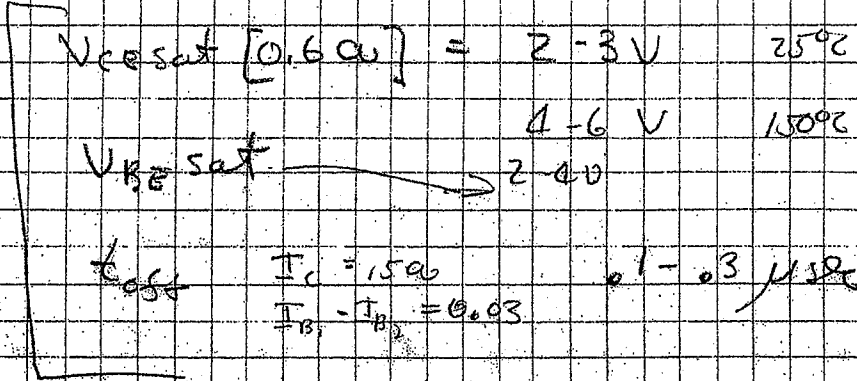
$f_T = 70 \text{ Mc}$

8W

$BV_{CEO} = 75V$

$h_{FE} \leq 3 \text{ amp}$

data



10696

See Supplement paper ~~8550~~ DT-1

2N1060

2/20/59

New product meeting

2/23/59

Wardell [unclear]

4:00 meeting

run large batches now -
20 wafers 0.4-0.6 cm diameter
diffused - ordered from production
100% storage time was ts + ts.

run thru 10⁴ final seals by end of April.

2/23/59

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Rad meeting

hi freq amplifier
 high power unit - FT 8000

μ miniaturization -

Wendell Jeffrey - back side alloying Au
AL alloying

U. work.

Discussion of Au vs Ag vs
first effort

JAH
 VAG
 MW
 JT - μ min
 J. Jeffrey

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ECCB Meeting

2/27/59

Eng raises 2-4 days.

Temp Eng Change Notice 1 month.

Notes

5:30

Highly desirable to make high voltage -
to be practical - only comm. trans - do
is to make standard devices.

11:00

make 2000 good/week by Oct 4
(or 1040) - i

11:40

won't replace 33% because it won't stand off water
3 ft max at 200.

3/18/59 139

R&D planning meeting

PRE PROD

PRODUCTION

1140

MAR 15

(OCT 1)

4500

JULY 1 (NEW BLDG)

pnph = 5500

JULY 1 (NEW BLDG)

1040 (338 replant) SEPT - OCT

6000

OCT 15 (when 1140 goes out)

(10 at 11)

Commitments

5500 - 1000 in Sept. (Peroneutronics)
500 by Dec. (Sperry)

low collage

3/12/59

New programs:SURFACES

OUTMODE THE MESA - OXIDE MASKING -

HIGH VOLTAGE

LEADS

Shell

- the base layers
- allowing the layers
- destruction under similar impurity interactions
- GaAs.

bar

Baron - high α level doping
oxide masking -
problem of device shorts
metals as gateways + lightness controllers
New phenomena devices - Reed model.

Woden

surface protection & stabilization (low melting point)
get leads out - glasses

surface problems in general - effect of ions

surface cleanliness - production & maintaining

high temp contacts -

long range - oxide & sulphide glasses - very conductivity

141
3/18/59

Day

power levels
1040-338
1040-

small geom. prop.

micro-min program

parametric amplification - various forms

Even

large areas - high power.

time schedule - personnel schedule
objectives

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4/5/59

low storage - low V_{cc} sat - high β

Storage < 100
fall ≈ 200

Small 1000 with no Au

mean f_{max} zone by 700

- small geometry - size considerations scale up by 1.5V

mean K_s factor on small geom. 5 ma collector

1010	worse for $\frac{1}{10}$	mean overdrive
4000	" " .02 miscible	offset voltage
		.03
		.13 .08

5/14/59

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R&D Meeting

Item time for report 1/2 hour - 1-2 members speakers
+ statements of future work.

Purpose R&D

supply a flow of ideas to rest of company
to see that company keeps abreast of new fields
sustaining function

maintain technical reputation of the company

Progress Reports - Section head accumulate
progress reports.

- no set time scale -

final reports written up to news - set up tel report
numbering systems.

W.B. - Electrochem Society Meeting - Phila.

Red Brown - high temp semiconductor

SiC - little real interest shown.

copy of Bi from St Hopkins - Sperry Rand.

Redox - GATs Prodes

10 volts.

Zn Diffusion

2.8 Kmc

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plasma-arc plating - Ni - for ~~plating~~ depositing
refractory materials

Prepart 5: up to 5000- μm
Baron coated - parts/billion

new lifetime meas. technique
11119 pt probe

pp - intermittent light
illumination

useful for lifetimes 50 - 350 μsec
hard for low lifetimes

END

Oct 1958

Balance sheet - end of fiscal year

Current assets	102,759
Fixed Assets	230,300
org. expense	<u>12,175</u>
	345,229

current liabilities	93,722
owe. Funded	<u>985,000</u>
	1,078,722

net worth	
cap. stock	1025
surplus	4,100
ret. loss	<u>738,100.91</u>

Net worth - 732,975.91

Overhead	Cost Sales	218,494
	R&D	<u>274,903</u>
		493,328

Net overhead 73,375

R&D expense:	Material	33,097
	Travel	108,854
	Overhead	<u>274,903</u>
		416,854